

Electron Microscopes and Cameras

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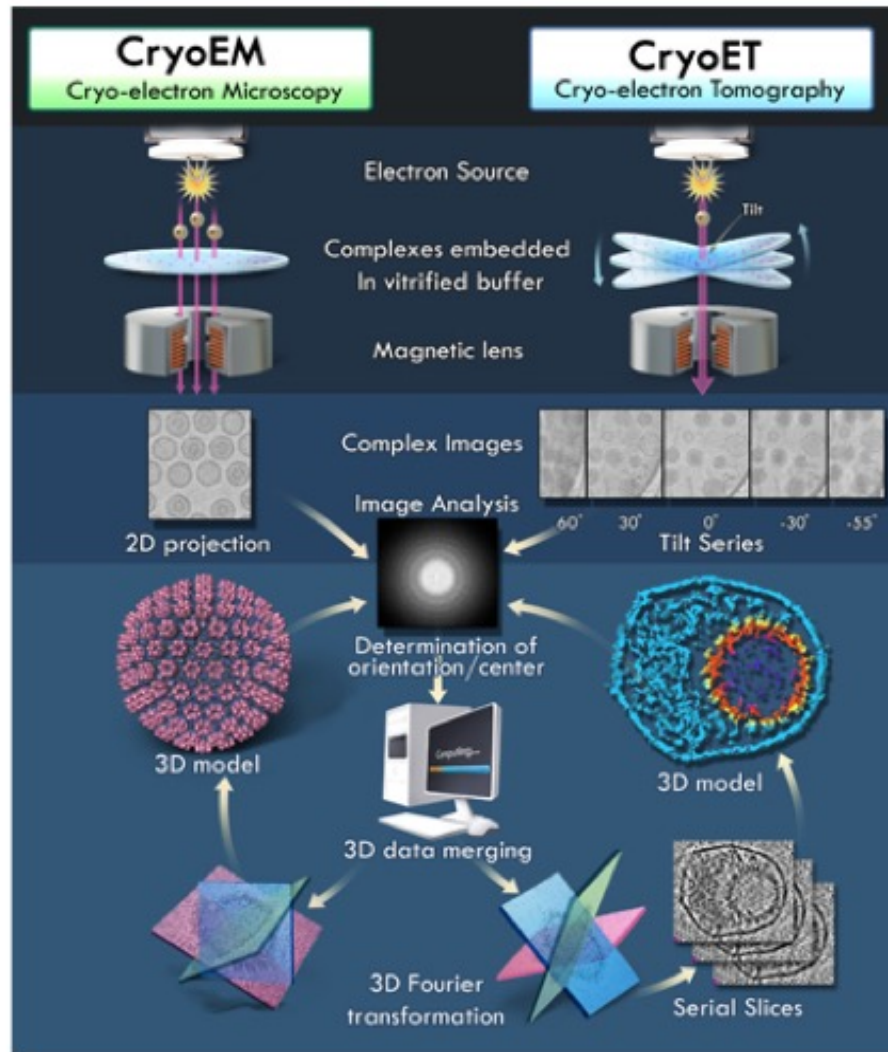
UMass Chan Medical School

LBMS cryo-EM course June 20, 2023

Transmission Cryo-Electron Microscopy

A tool used by structural biologists to study
molecular nanomachines

Gabriel Lander, Thesis Defense 2009



(<http://www.eicn.ucla.edu/xiaorui>)

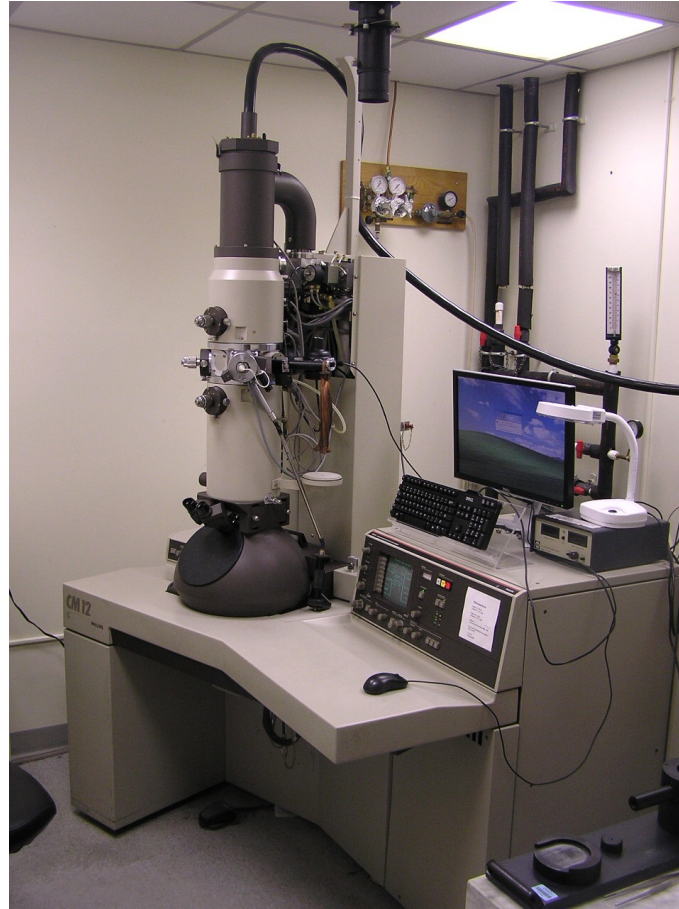
Outline

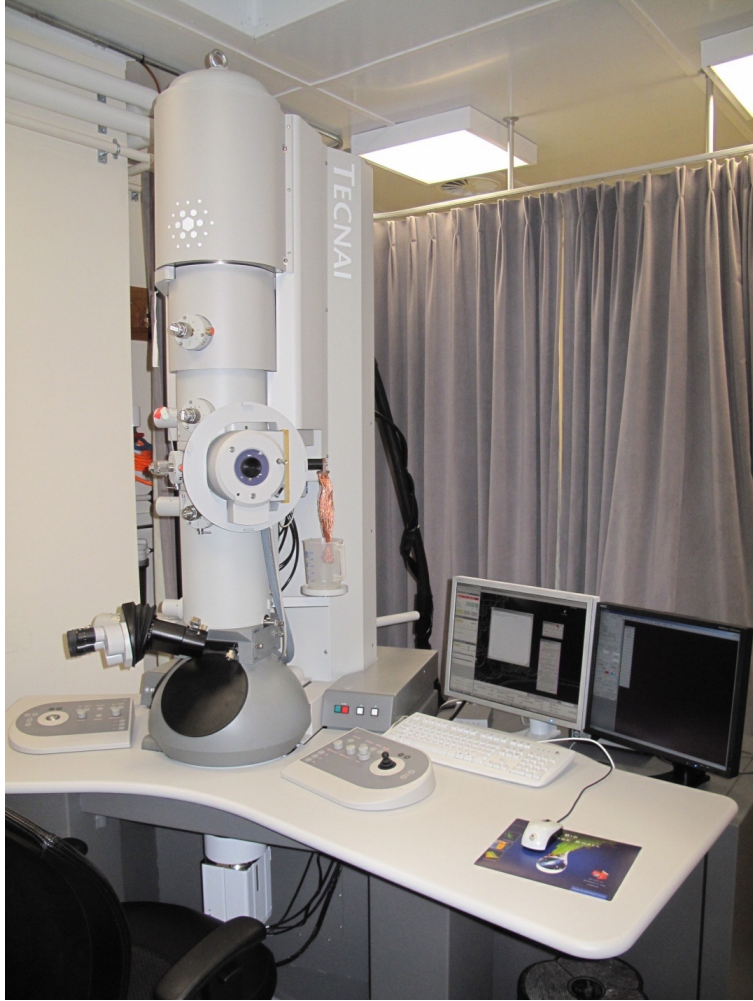
- I. Electron Microscope & Optics
- II. Cameras – from CCD to DED
- III. Advanced Software Control

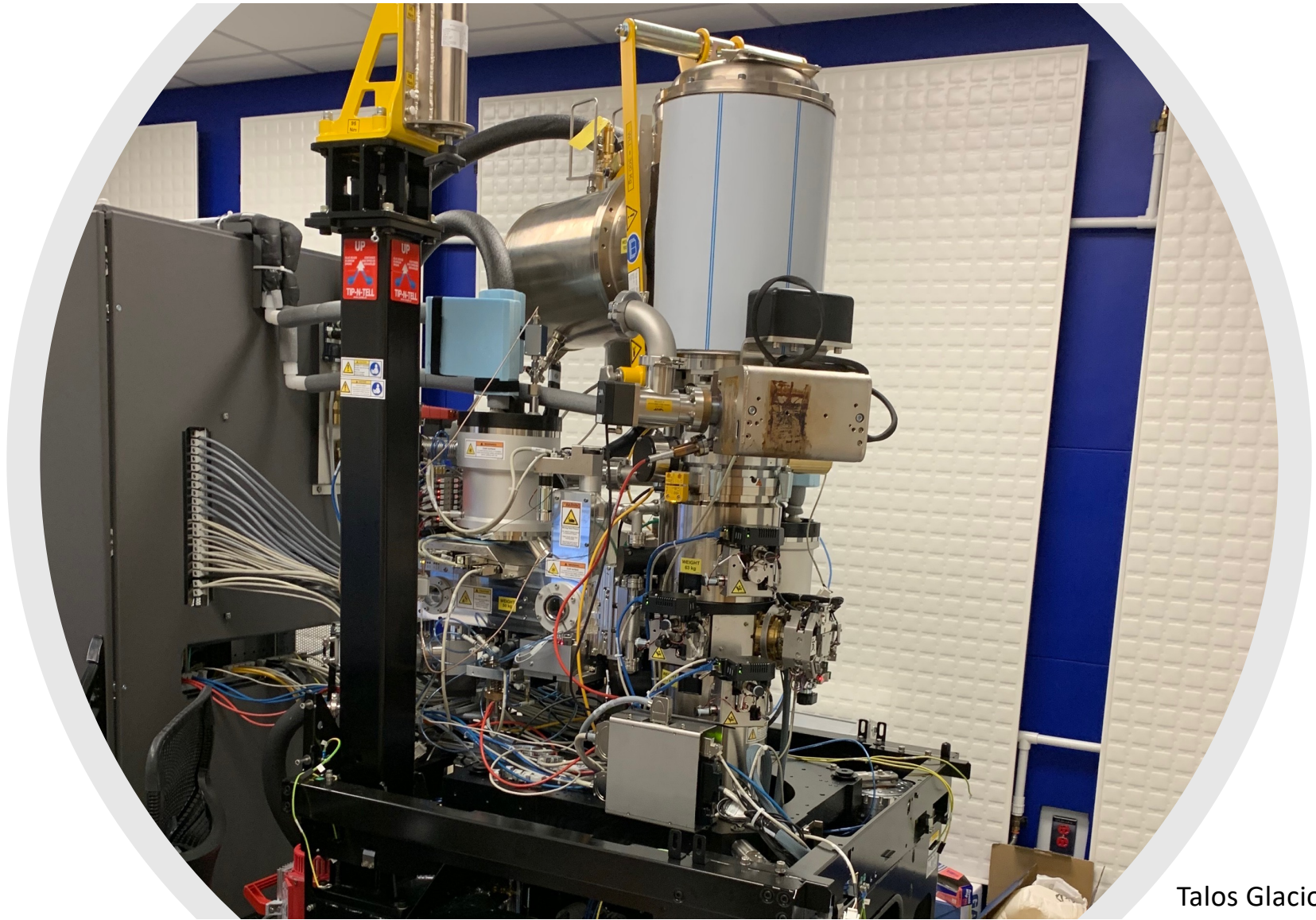
I. Electron Microscope & Optics



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- First EM was built by Ernst Ruska and Max Knoll in 1931







Talos Glacios @ UMass

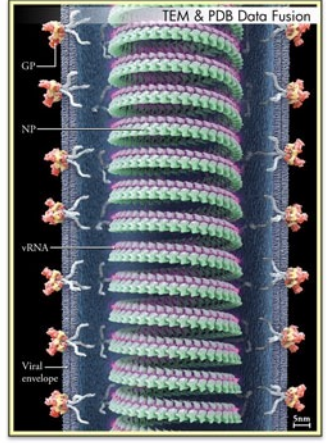
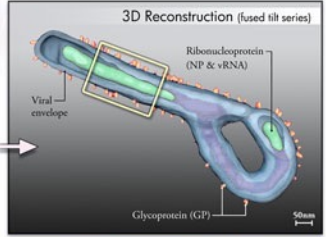
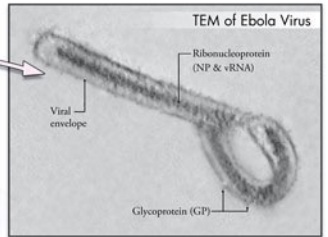
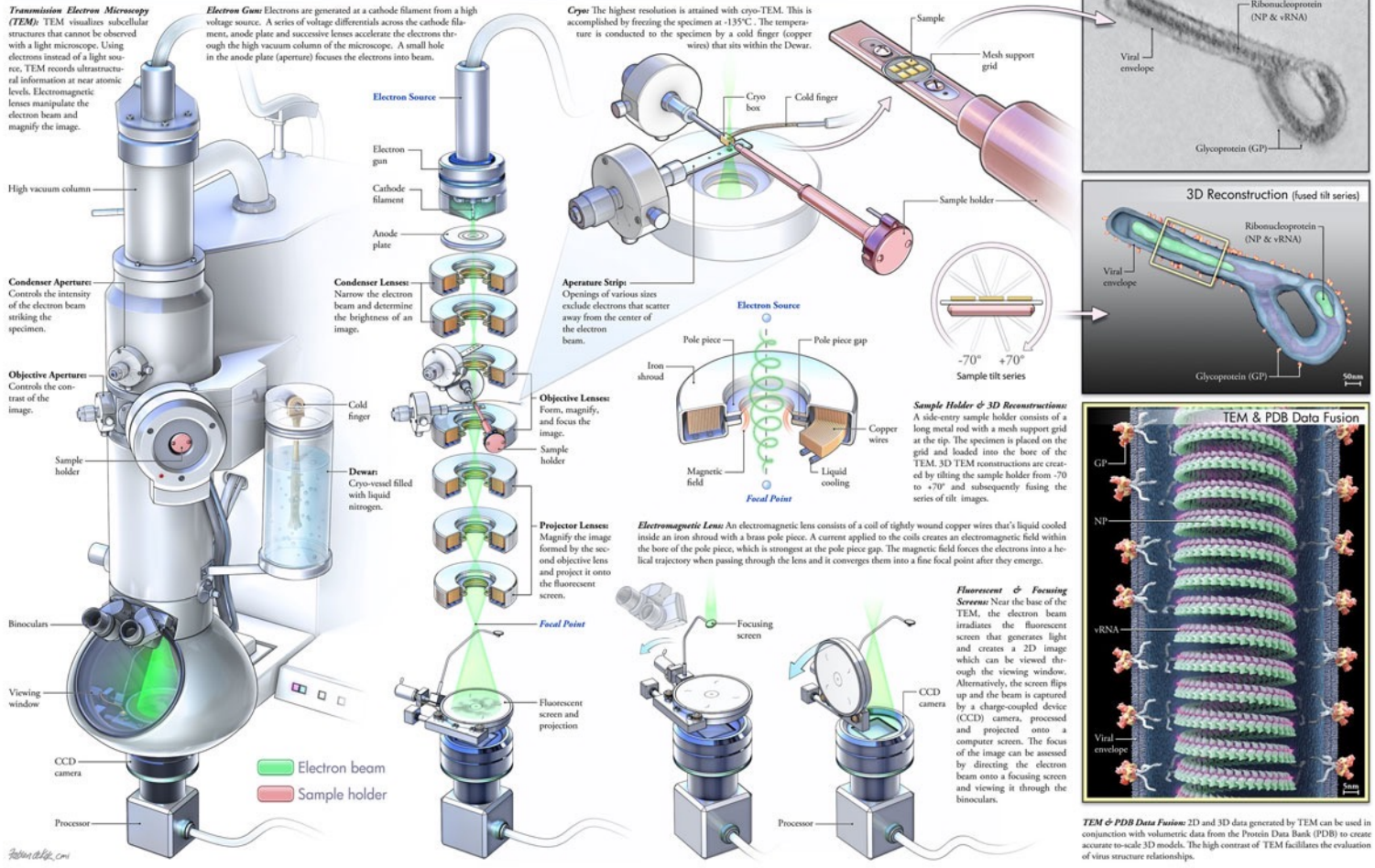
Transmission Electron Microscopy

Structure, Function & 3D Reconstruction

Transmission Electron Microscopy (TEM): TEM visualizes subcellular structures that cannot be observed with a light microscope. Using electrons instead of a light source, TEM records ultrastructural information at near atomic levels. Electromagnetic lenses manipulate the electron beam and magnify the image.

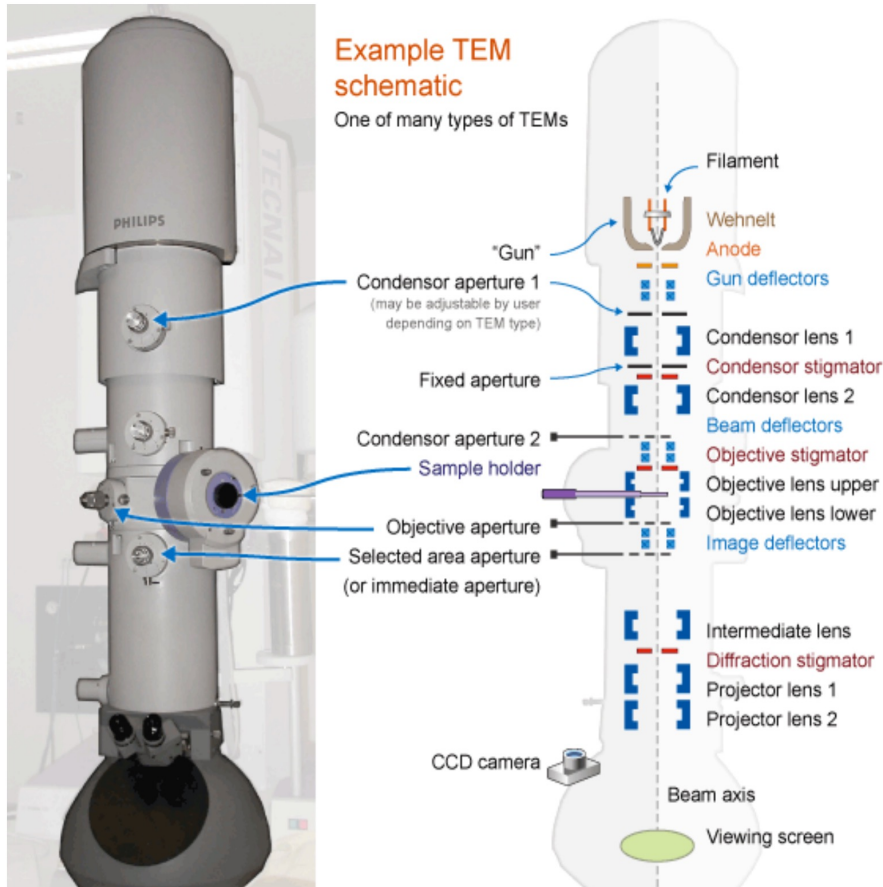
Electron Gun: Electrons are generated at a cathode filament from a high voltage source. A series of voltage differentials across the cathode filament, anode plate and successive lenses accelerate the electrons through the high vacuum column of the microscope. A small hole in the anode plate (aperture) focuses the electrons into beam.

Cryo: The highest resolution is attained with cryo-TEM. This is accomplished by freezing the specimen at -135°C. The temperature is conducted to the specimen by a cold finger (copper wires) that sits within the Dewar.



TEM & PDB Data Fusion: 2D and 3D data generated by TEM can be used in conjunction with volumetric data from the Protein Data Bank (PDB) to create accurate to-scale 3D models. The high contrast of TEM facilitates the evaluation of virus structure relationships.

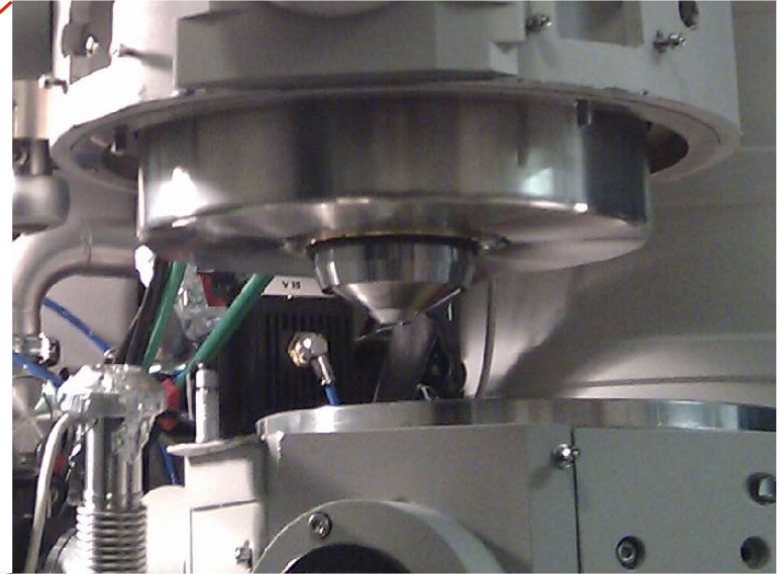
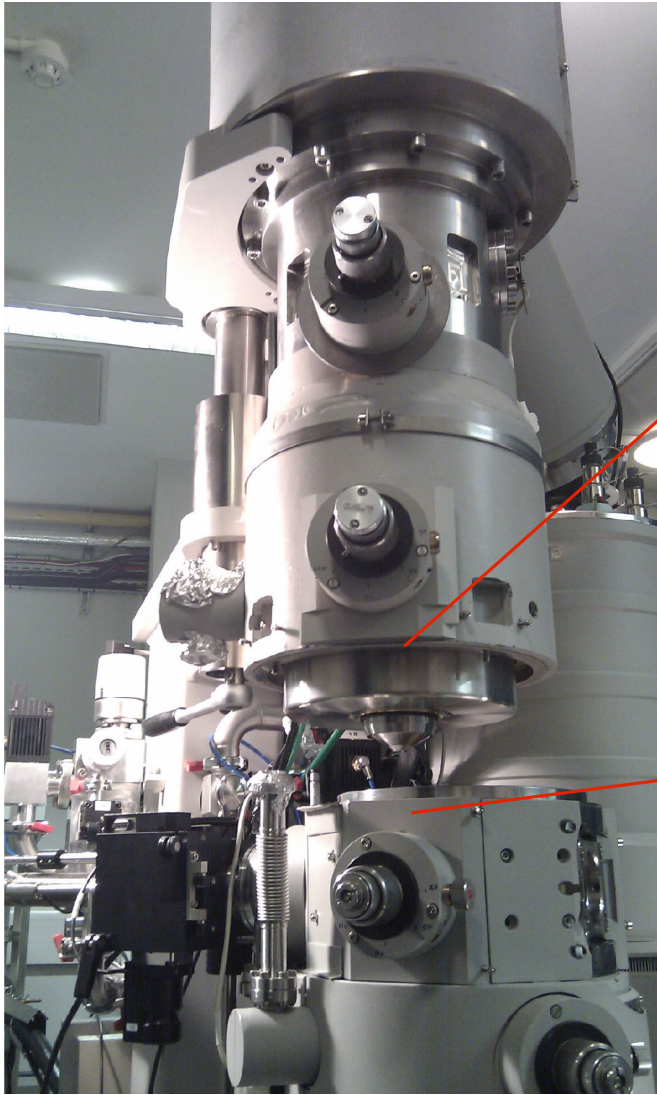
Anatomy of a TEM



1. Electron Gun – beam source
2. Illumination System – Condenser lenses
3. Imaging System – Objective lenses
4. Projection system – Projector lenses
5. Recording system - detectors

Hardware Components

1. Electromagnetic lenses (condenser, objective, projectors)
2. Alignment coils, stigmator coils, blanker & shutter coils
3. Apertures
4. Cameras

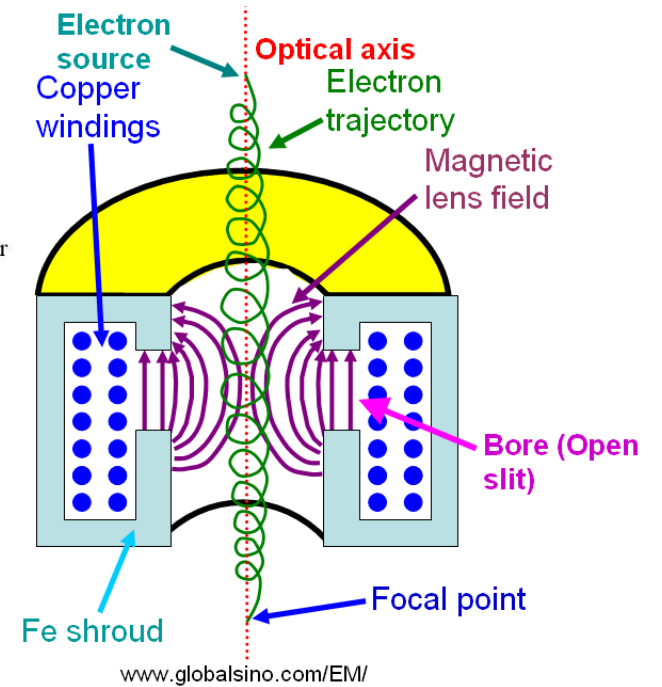
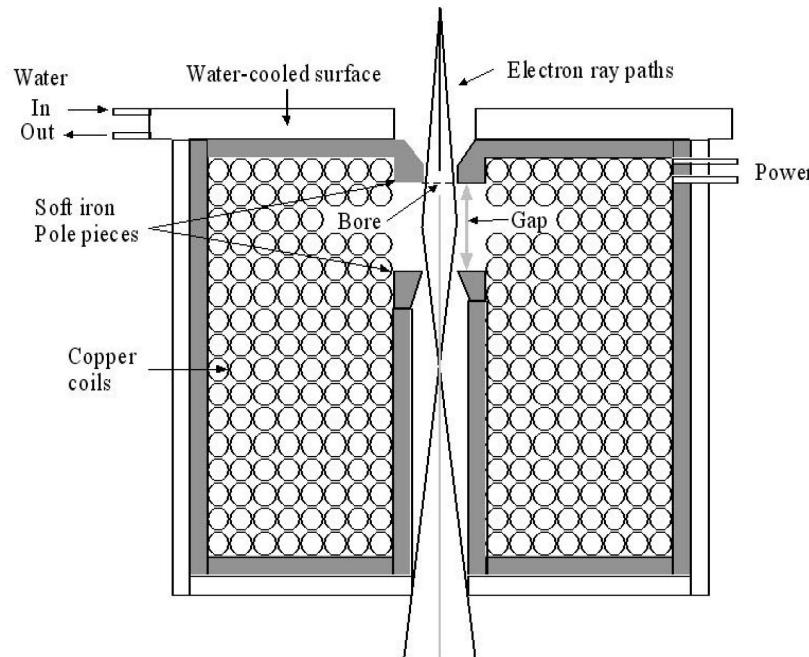


Magnetic Lens

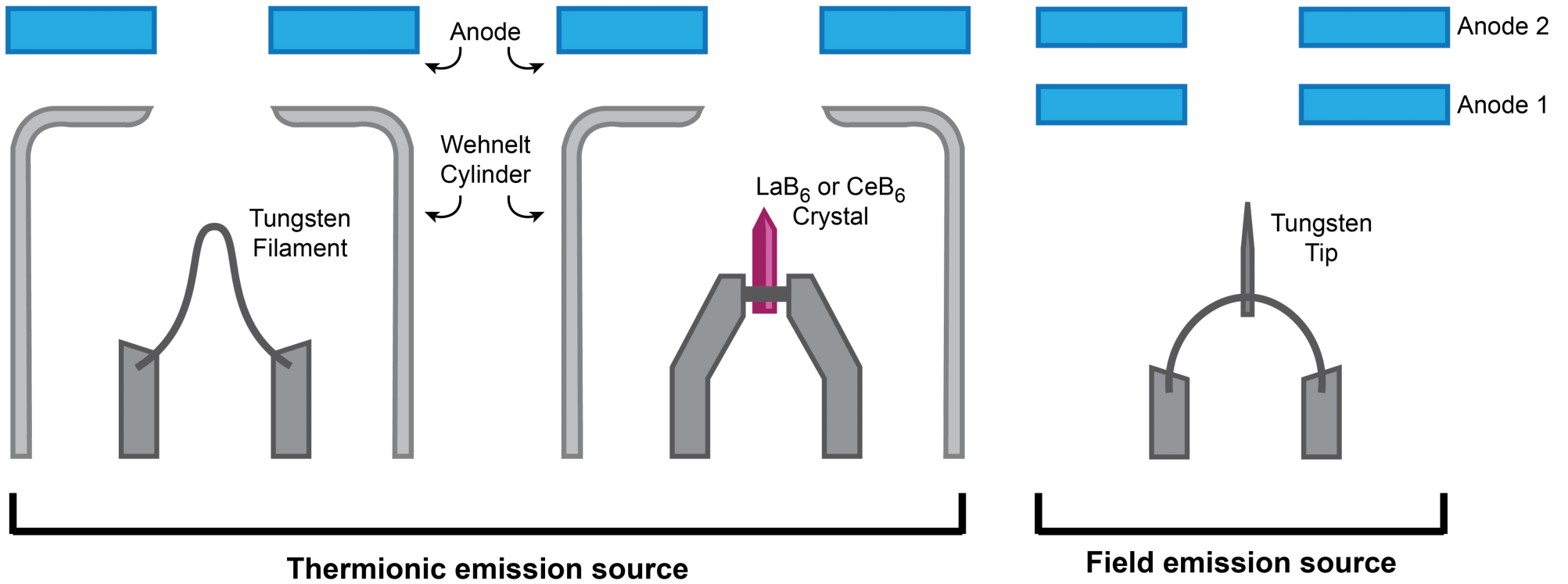
Concentrate flux

Field varies

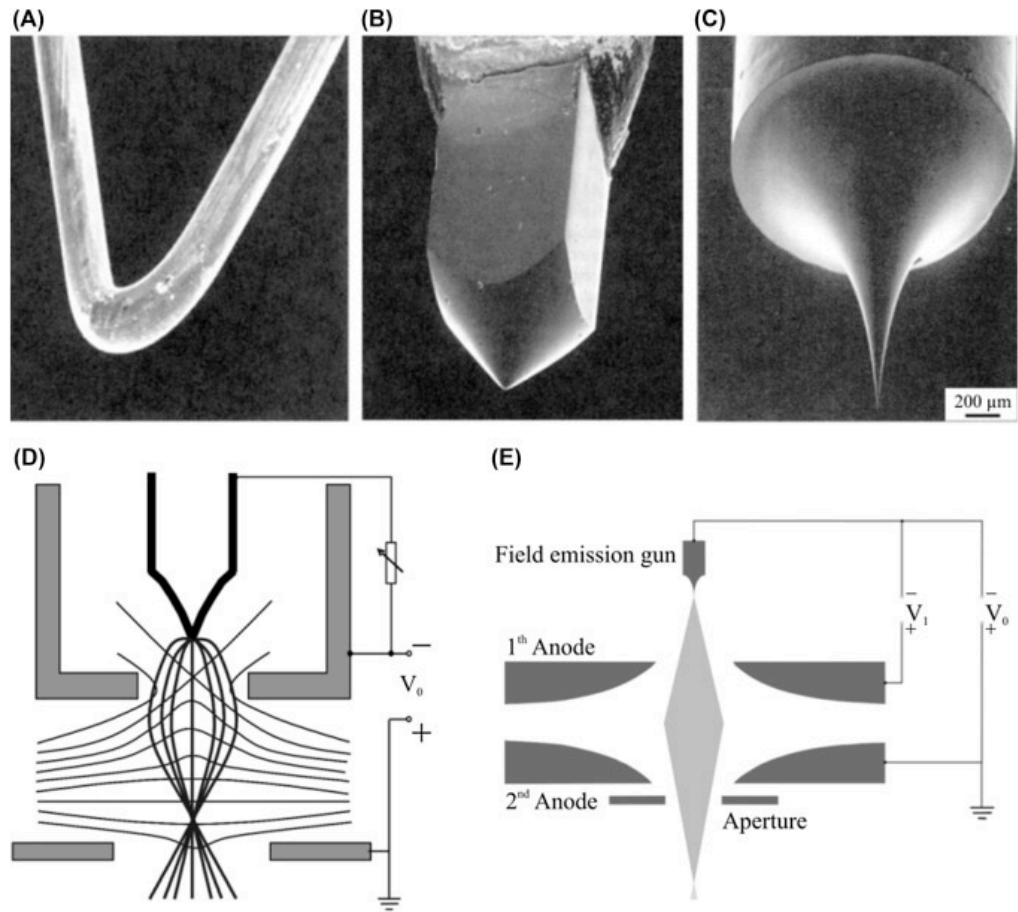
Zero force on axial electrons



Beam Source



Beam Source



FEG Beam Source Types

Schottky-type

1. High temperature ~ 1800 K
2. Energy spread ~ 0.7 eV
3. Stable beam Intensity

Cold-FEG

1. Room temperature
2. Energy spread ~ 0.3 eV
3. Decrease with time

Coherence of a Beam Source

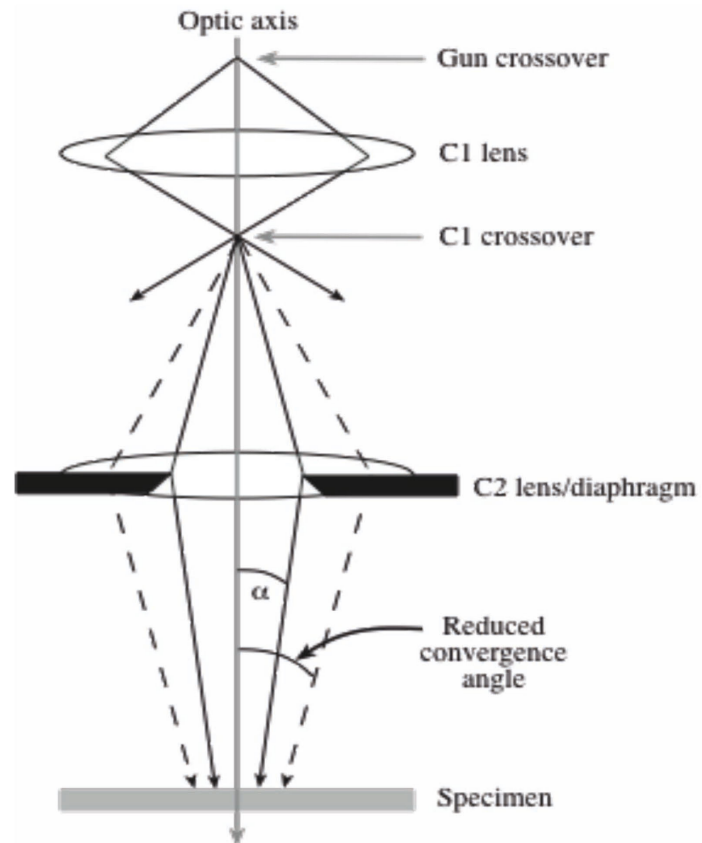
Spatial Coherence -- electrons emitting from small area

Temporal Coherence -- narrow wavelength range

The Basic Electron Condenser System

Most TEMs 2 lenses + 1 aperture

Krios: 3 lenses + 1 aperture



Aberrations due to Imperfect Lens

- Defocus
- Astigmatism
- Coma
- Spherical aberration
- CTF
-

They are corrected with **additional lenses / coils** In the microscope

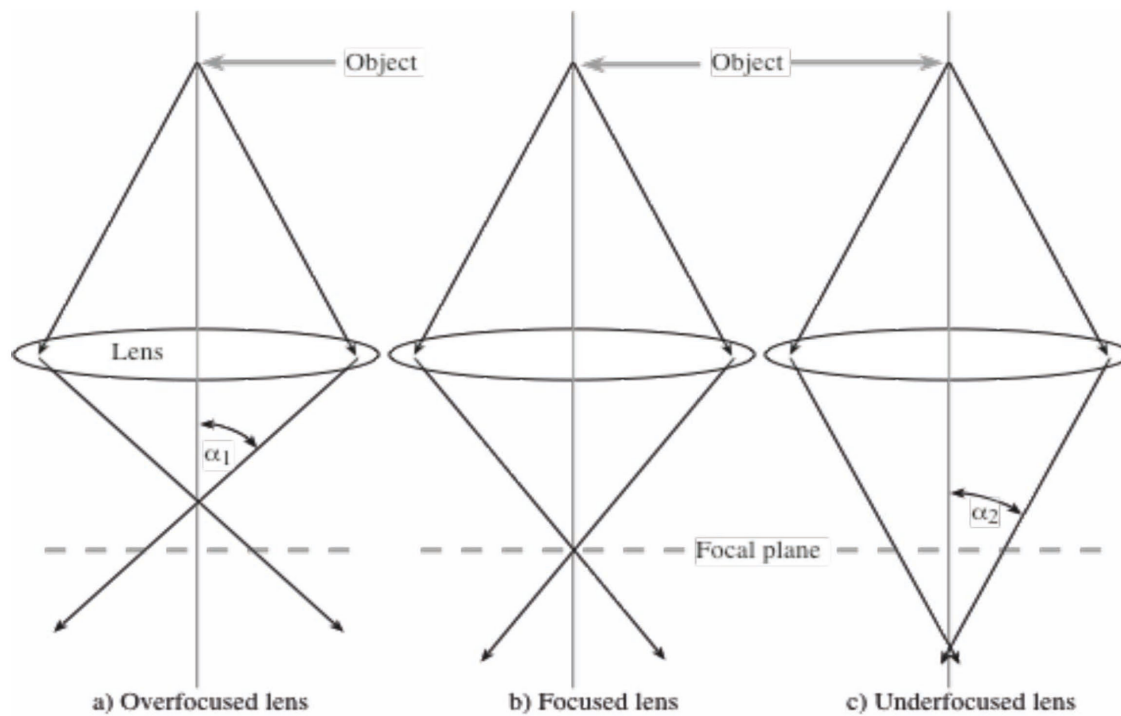
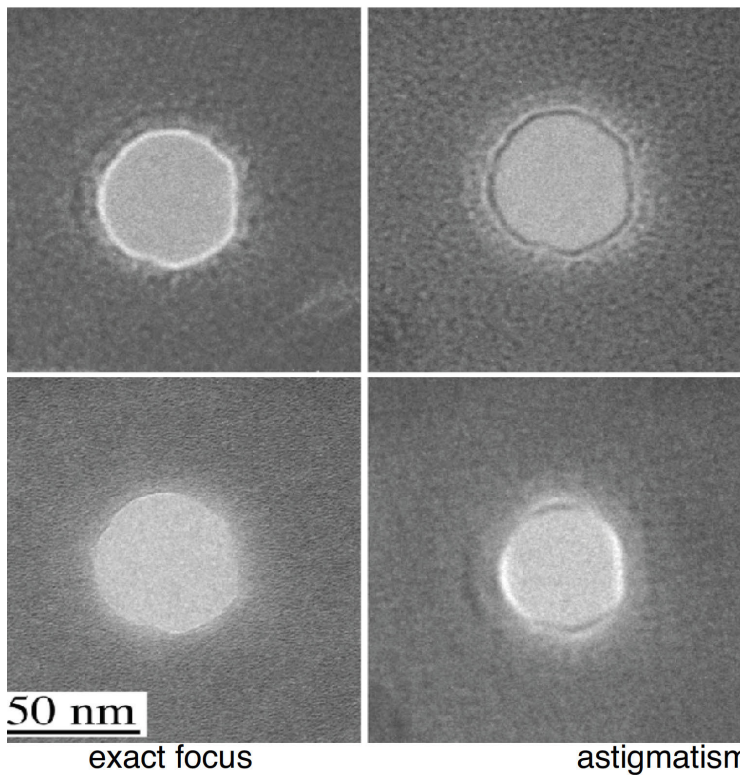
OR

In **software** after the image is collected ("CTF correction")

Focus terminology

underfocus

overfocus

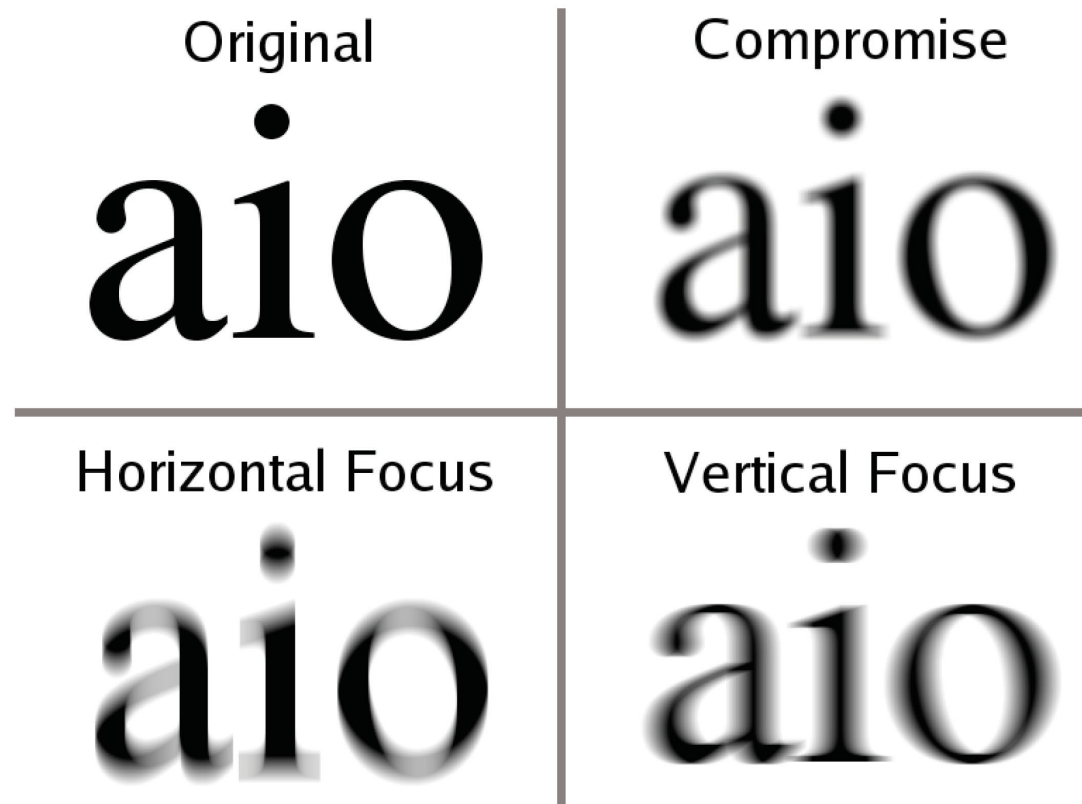


Too strong

Just right

Too weak

Astigmatism (example)



Condenser Beam Astigmatism Correction

Just change focus

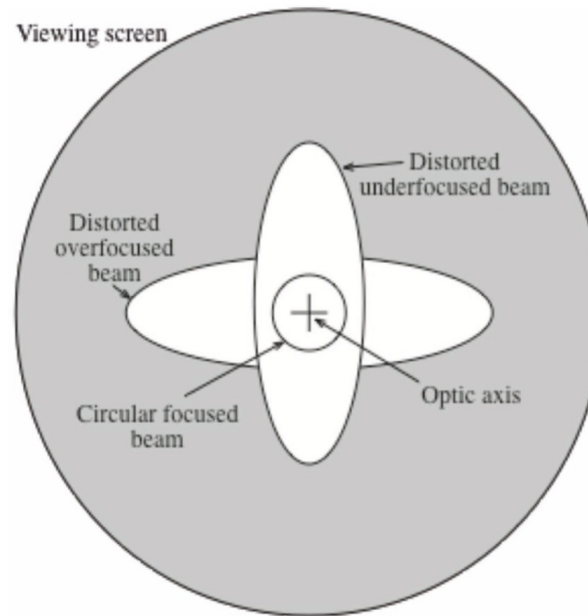
Underfocus



90°->



Overfocus



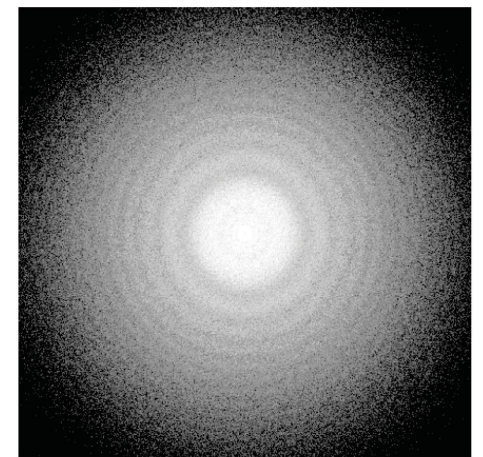
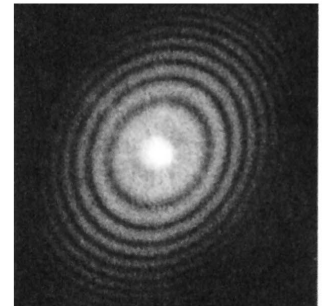
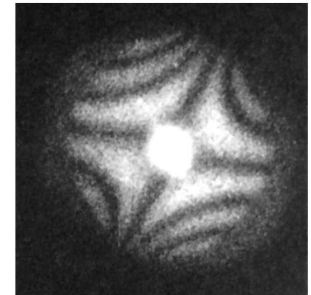
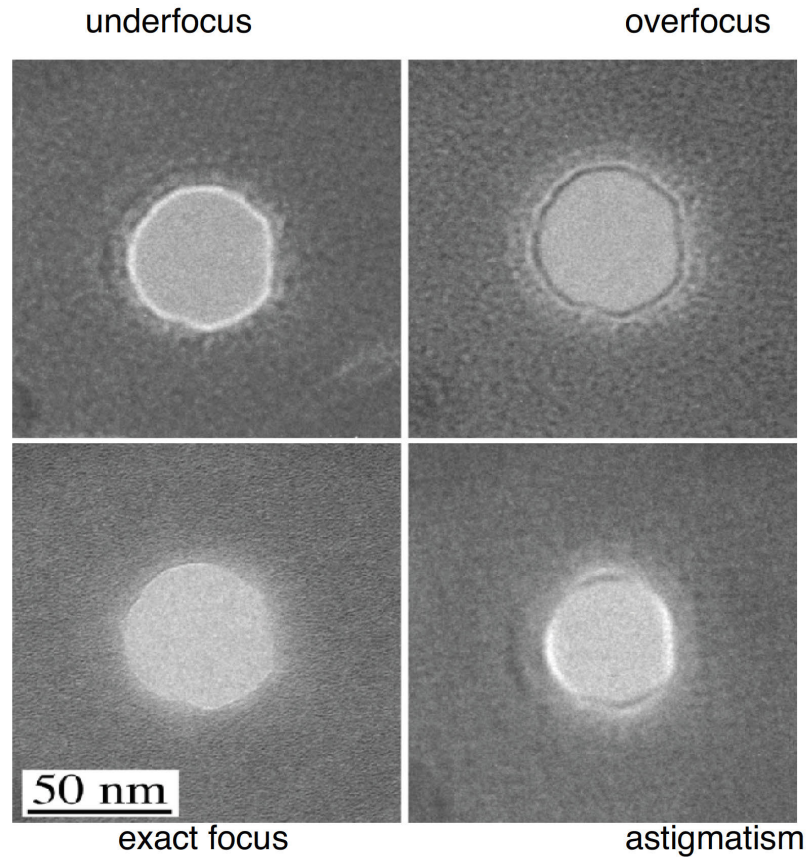
Astigmatism Correction

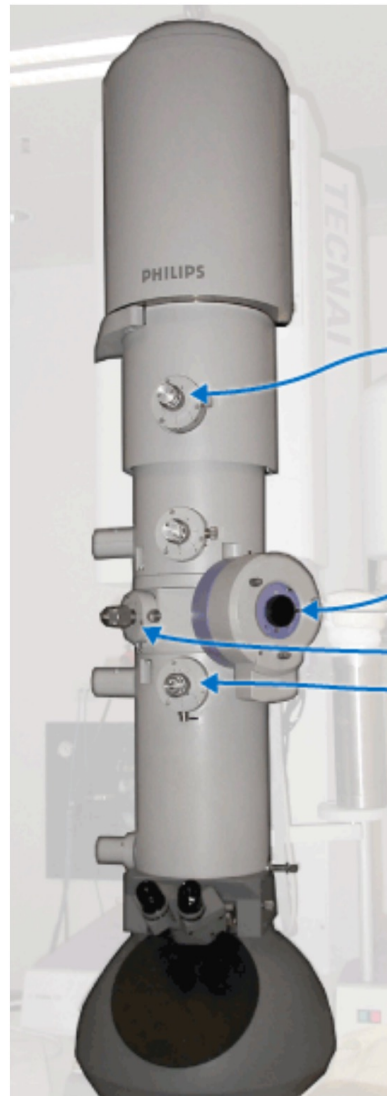
Correcting the astigmatism on the objective lens

Routine alignment using Fresnel fringe

More accurate with FFT

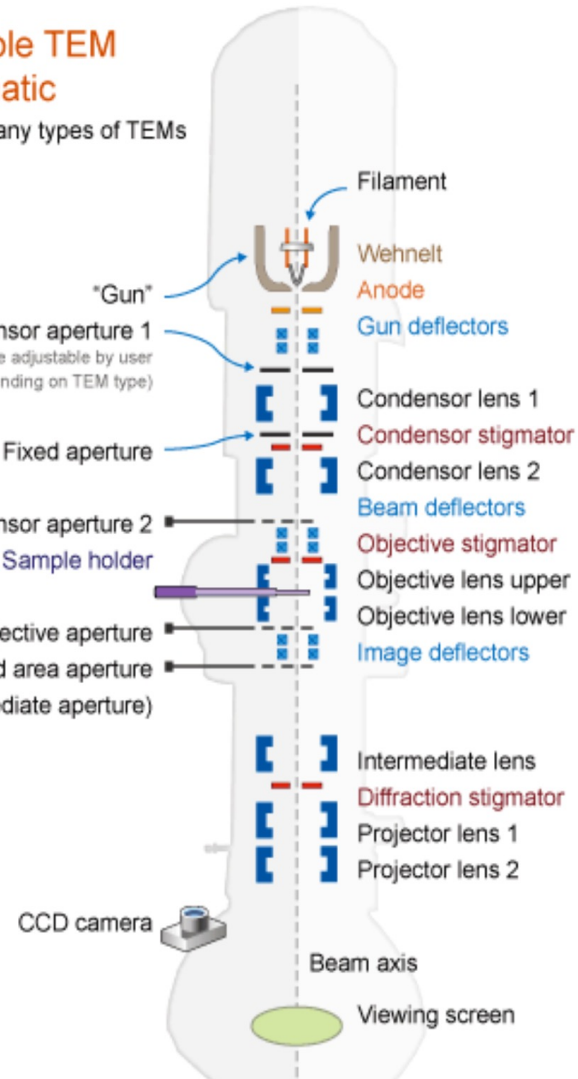
Remember to correct the condenser lens too



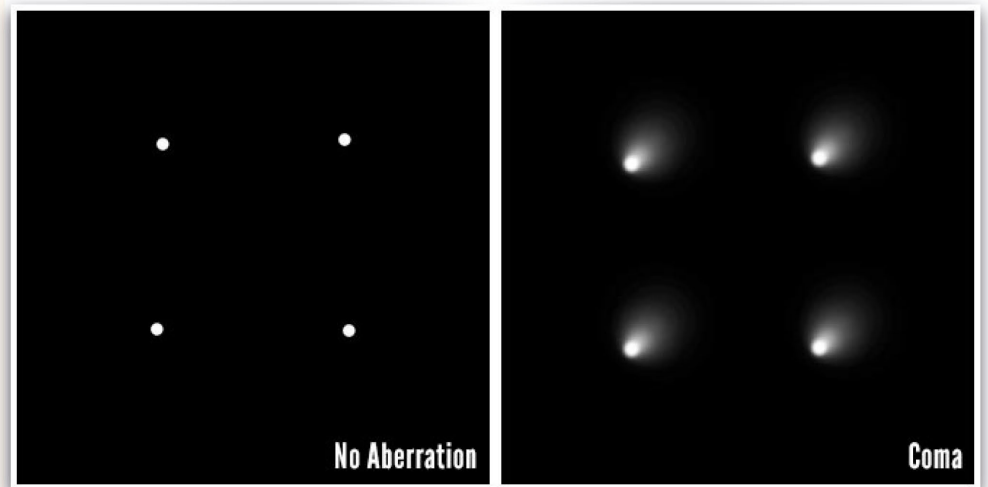
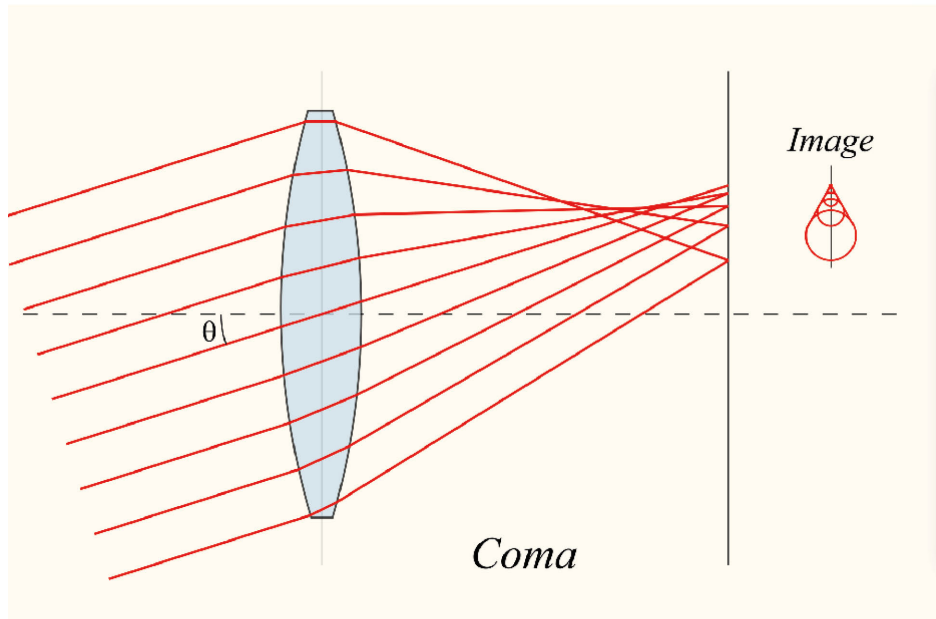


Example TEM schematic

One of many types of TEMs

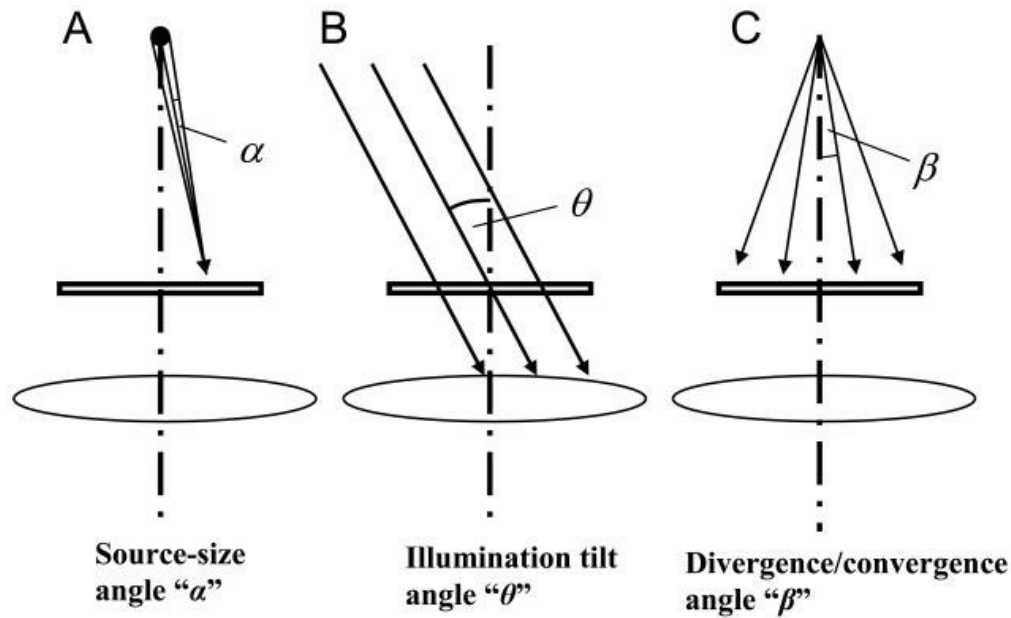


Coma – tilted beam



Example image from I. Norman

Illumination Conditions



Overfocused beam

Axial Coma

Off-axis Coma

Beam Tilt Introduces:

$$\Delta z_{\text{effective}} - \Delta z_{\text{no beam tilt}} = -2C_s \theta^2;$$

Excess of increment of defocus

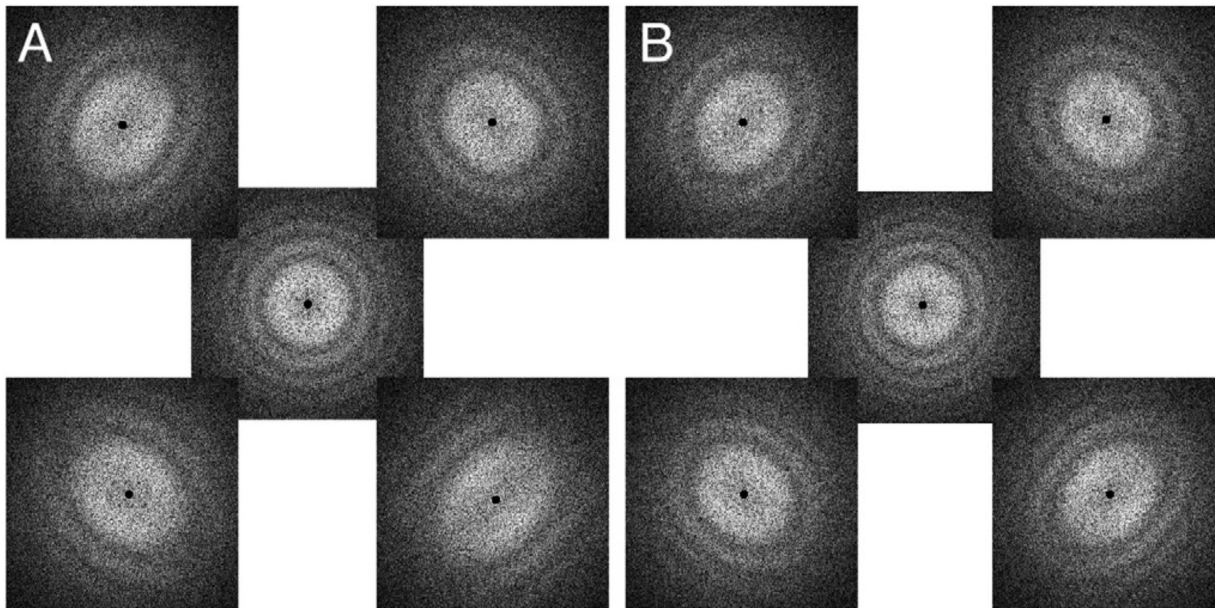
$$A_{\text{beam tilt}} = C_s \theta^2;$$

Excess astigmatism

$$\text{Phase error} = 2\pi \theta C_s \lambda^2 s^3 (\hat{\theta} \cdot \hat{\mathbf{s}})$$

Coma -> Phase Error

Coma Free – by minimizing beam tilt



1. Voltage Centering
2. Current Centering
3. Zemlin Tableaux

Parallel Beam – a verifying procedure

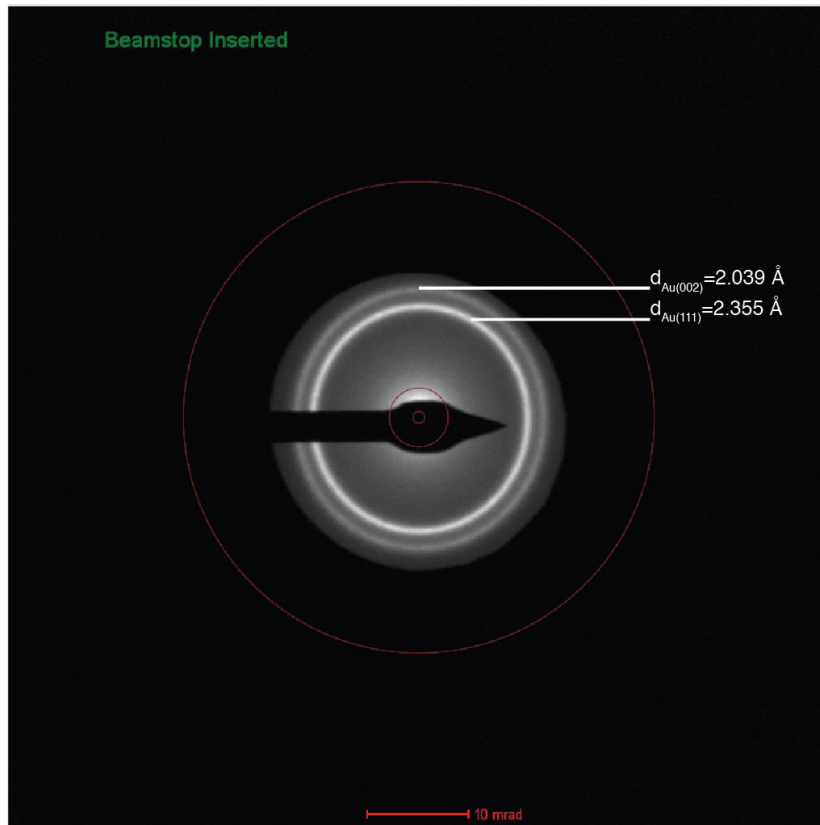
$$\Delta z_{\text{effective}} - \Delta z_{\text{no beam tilt}} = -2C_s \theta^2;$$

$$A_{\text{beam tilt}} = C_s \theta^2;$$

With a large beam tilt ~ 10 mrad

- Take an image
- Perform FFT of sub-areas
- Compare defocus and astigmatism of them
- Adjust Intensity (C2) & repeat above

Parallel Beam – a practical procedure



Parallel illumination on a Talos Arctica

- Eucentric focus
- Insert Obj Aperture in Diffr. mode
- Adjust Focus Knob until aperture edge is sharp
- Adjust Intensity (C2) until diff. rings are sharp

M Herzik et al, Nature Methods **14**, pages 1075–1078 (2017)

Parallel Beam – An Alternative Procedure

Questions / Concerns:

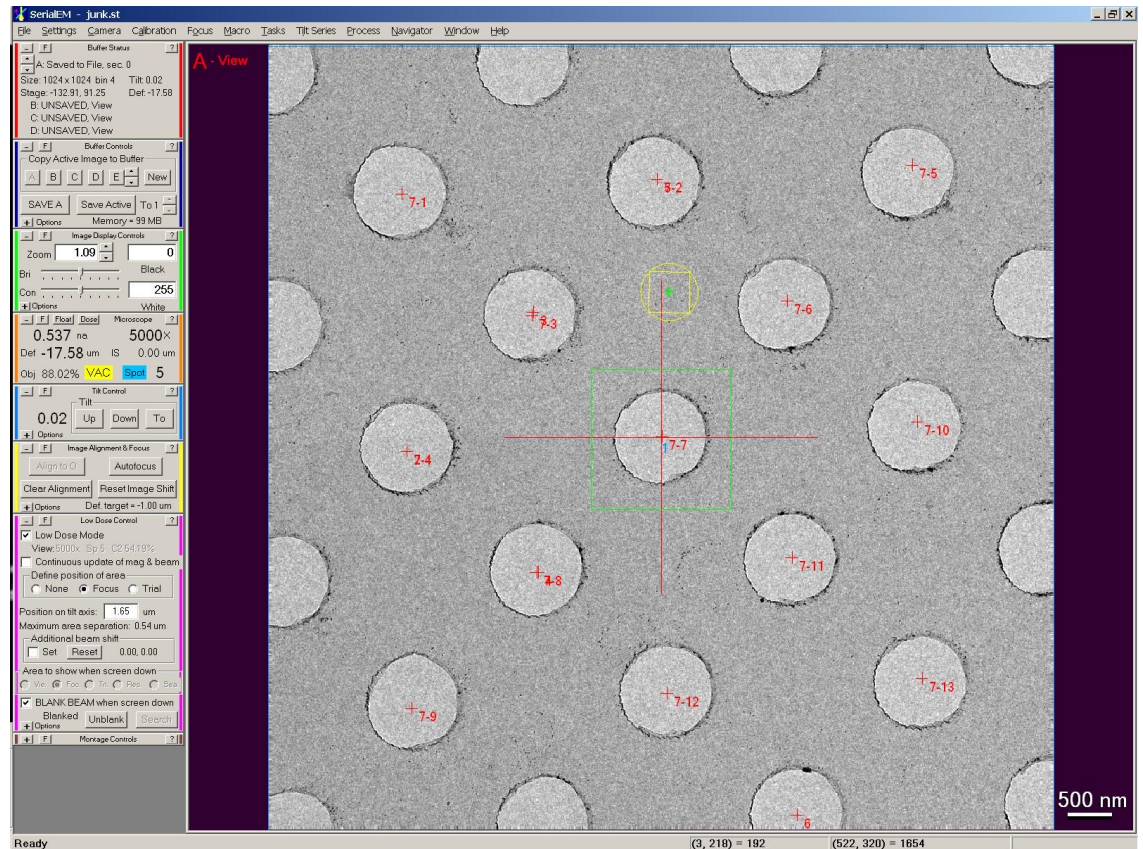
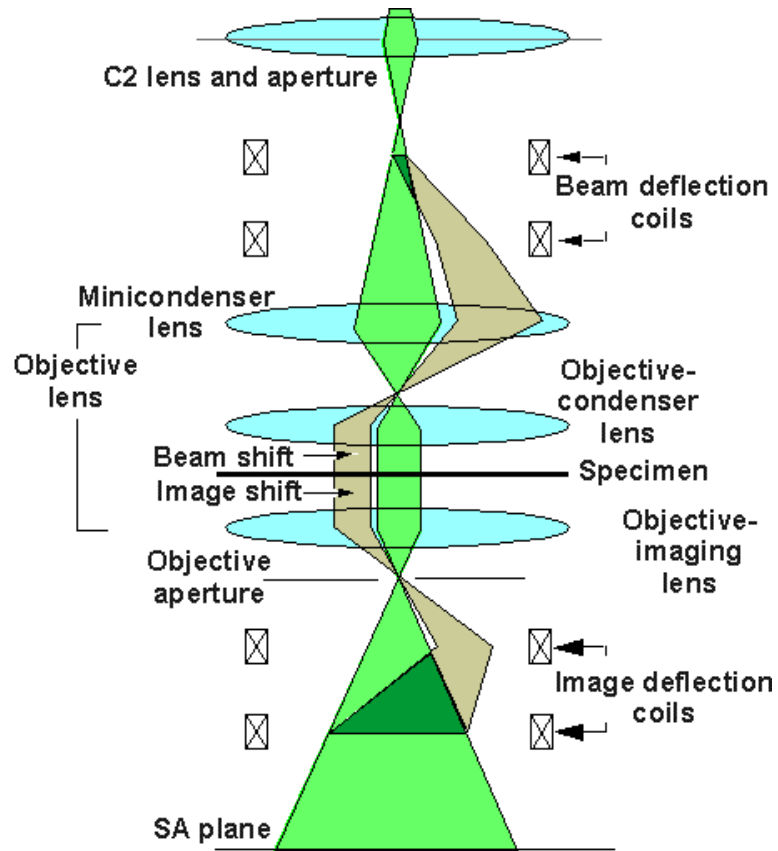
1. Obj Aperture might not sit at Back Focal Plane
2. Hard to find precise intermediate lens value for sharp aperture edge

An Alternative Method

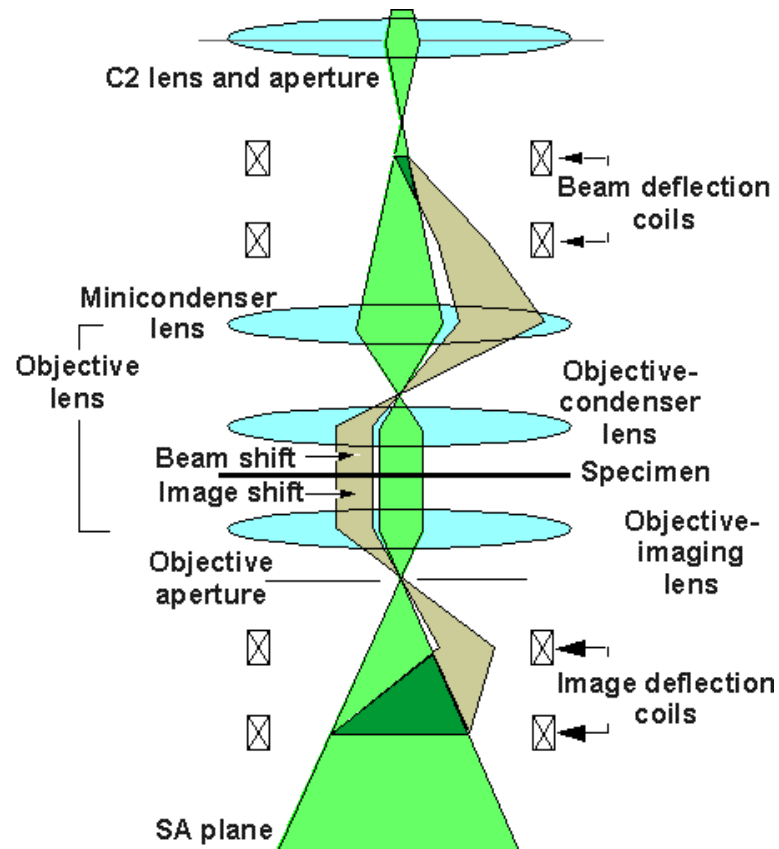
1. Z at Eucentricity Height
2. Measure pixelsizes with different C2 values
3. Z + 100 um
4. Measure pixelsize with different C2 values
5. Find interception of two lines plotted.

* On Krios with C3, the term is **ImageDistanceOffset**

Beam-Image Shift



Beam-Image Shift

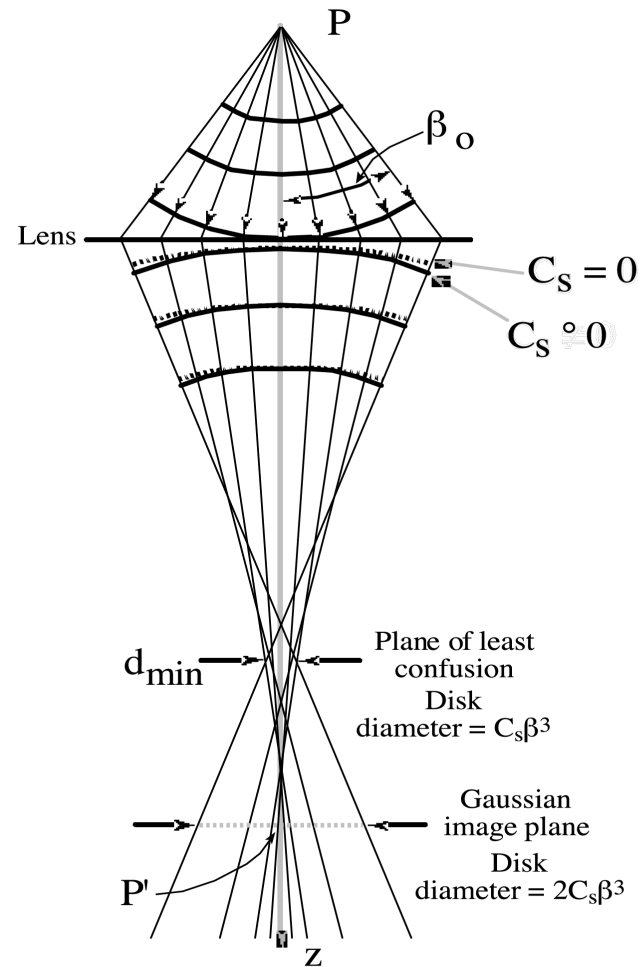


1. Is a single action of microscope
2. Used in Low Dose Conditions
3. Used in high-throughput exposures
4. Induces aberrations due to
 - Axial coma
 - Astigmatism

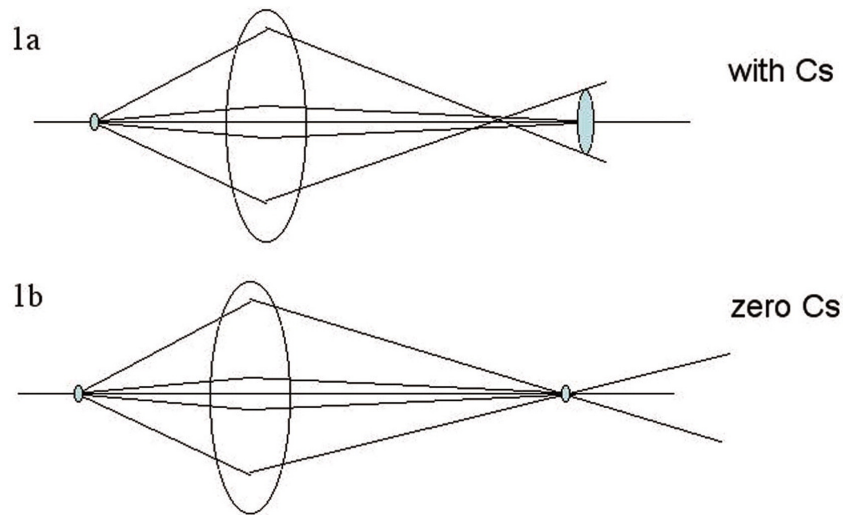
Spherical Aberration

Lens is stronger off axis

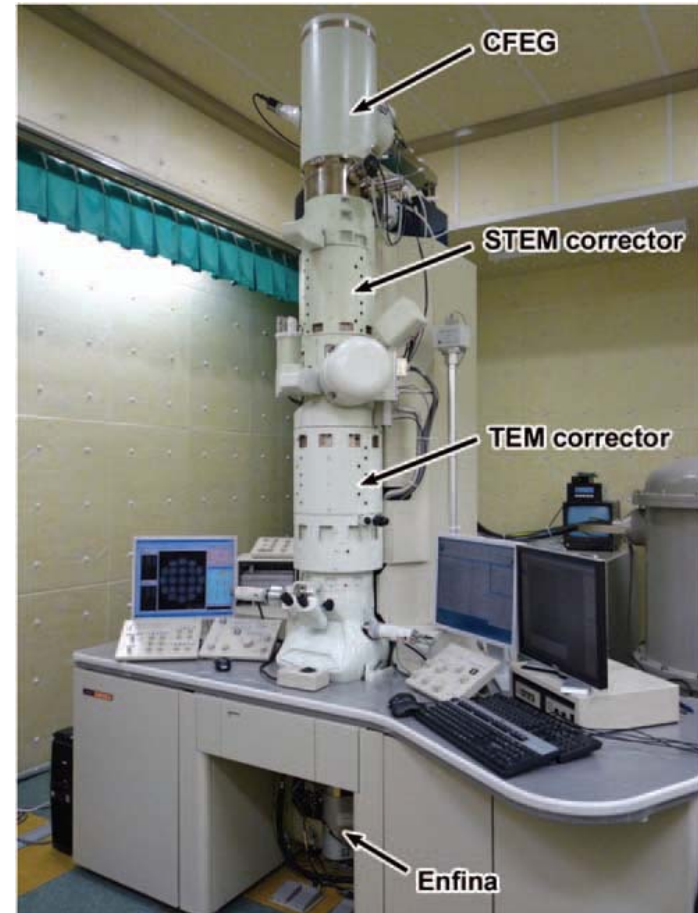
Plane of least confusion



Spherical Aberration & Cs Corrector



Cs = 0.5 – 3.0mm



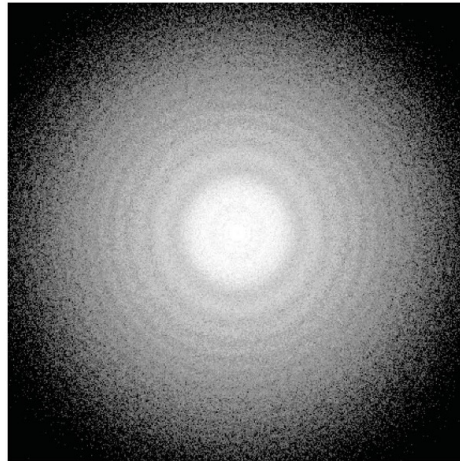
CTF

Phil. Trans. Roy. Soc. Lond. B. **261**, 105–118 (1971) [105]
Printed in Great Britain

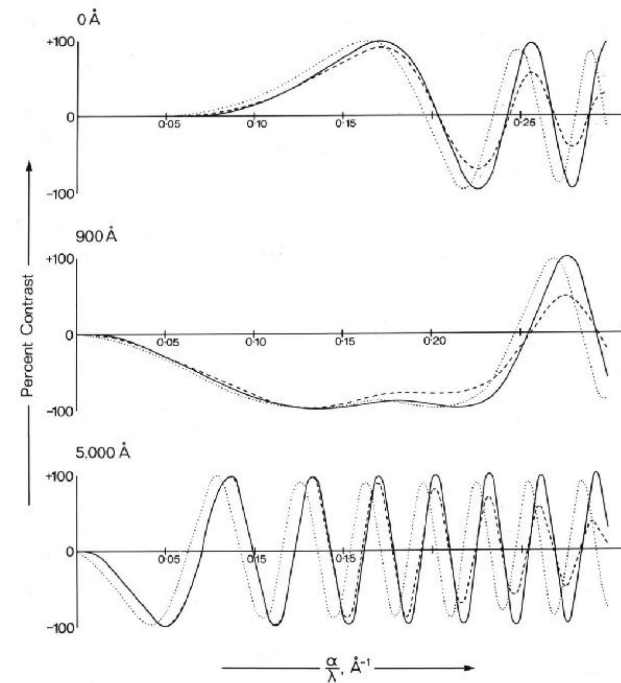
Measurement and compensation of defocusing and aberrations by Fourier processing of electron micrographs

BY H. P. ERICKSON AND A. KLUG, F.R.S.
Medical Research Council Laboratory of Molecular Biology, Cambridge

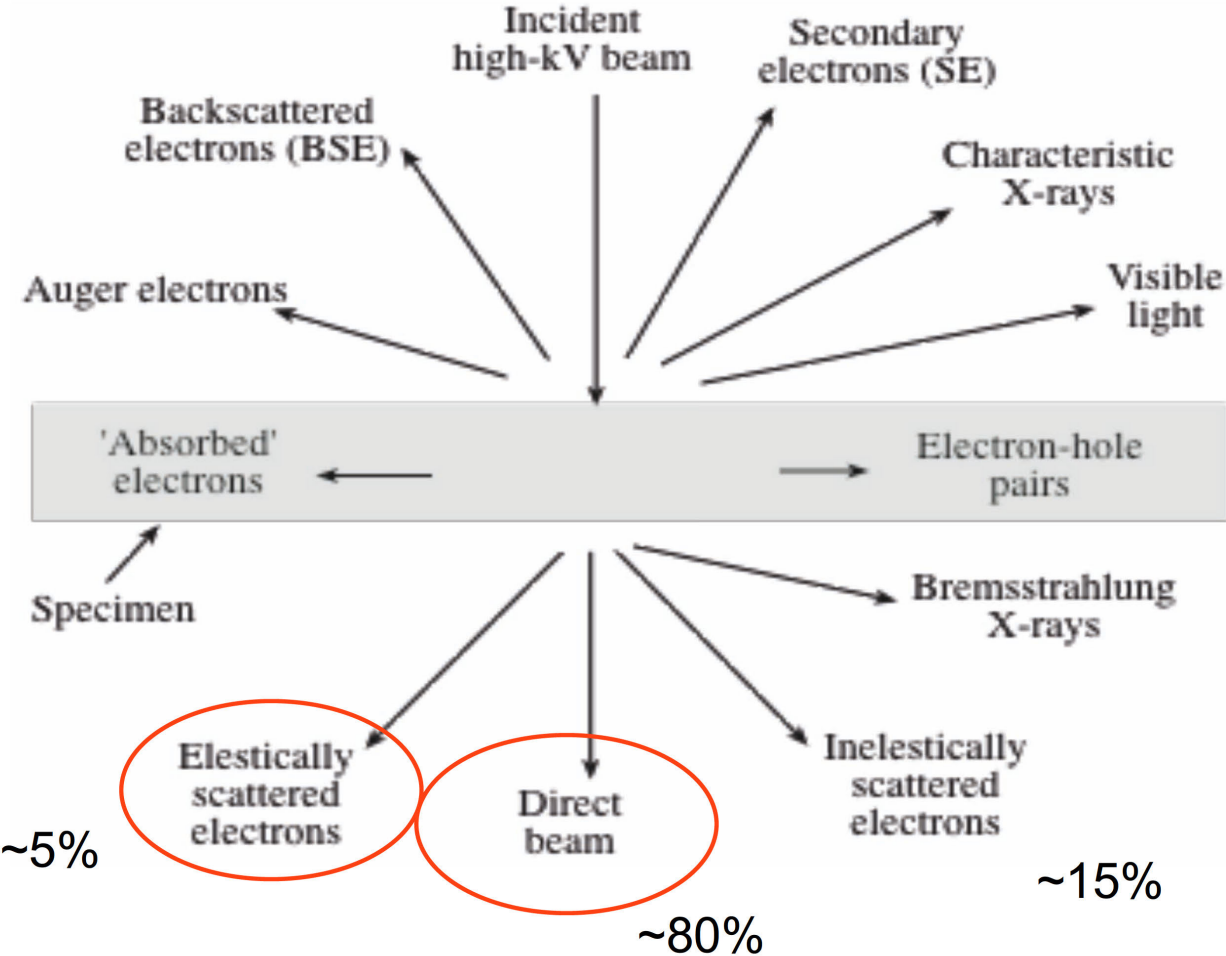
Contrast
Transfer
Function



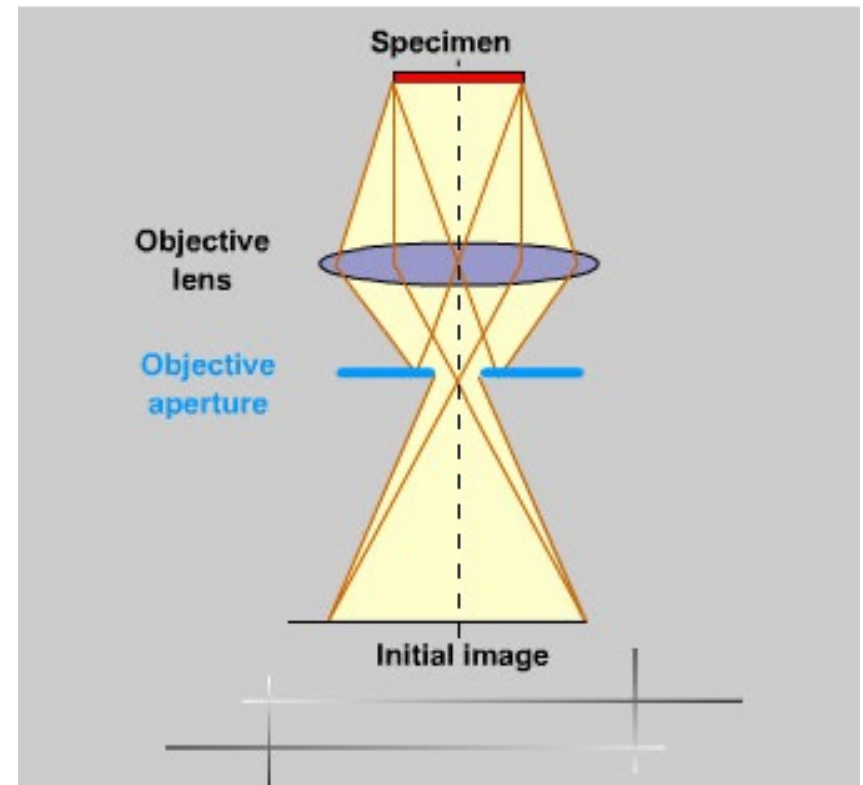
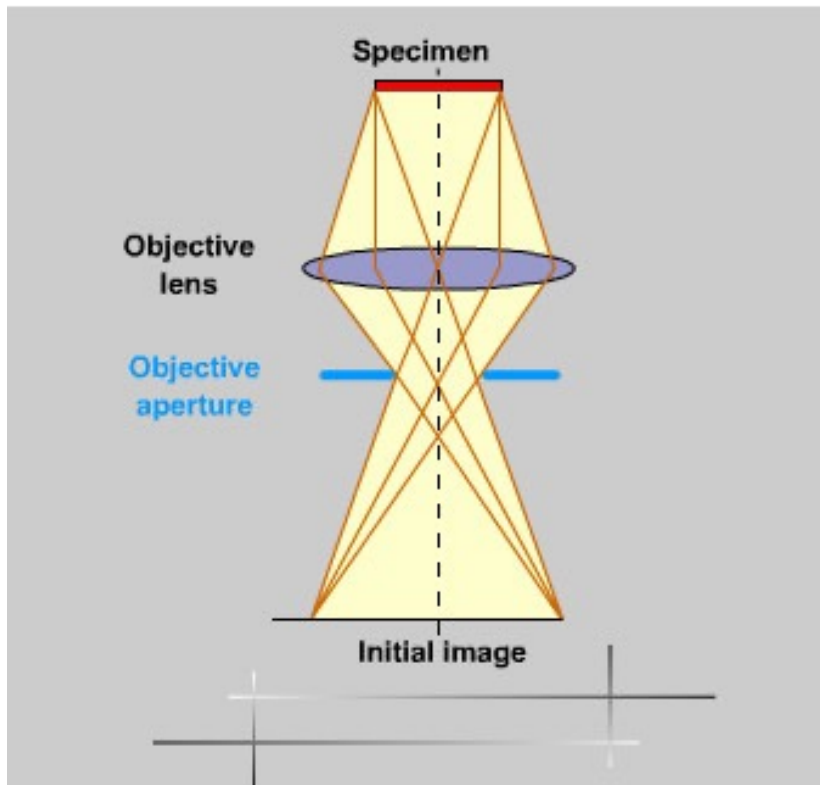
Can be corrected by software as post-process



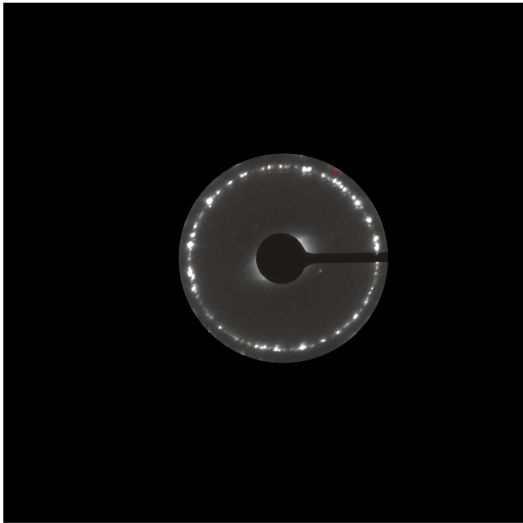
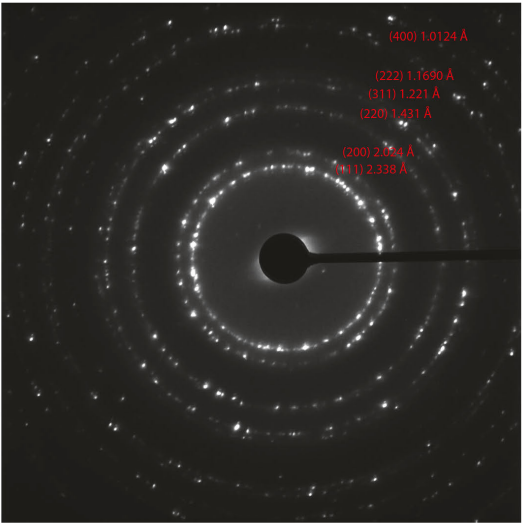
Large Number of Signals



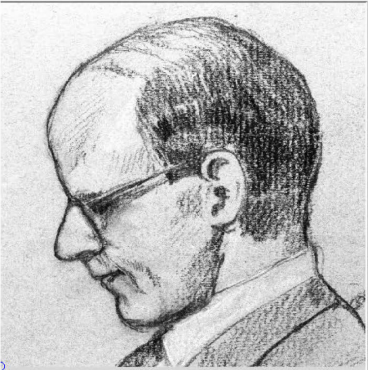
Objective Aperture



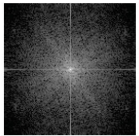
Objective aperture



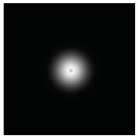
Beware...



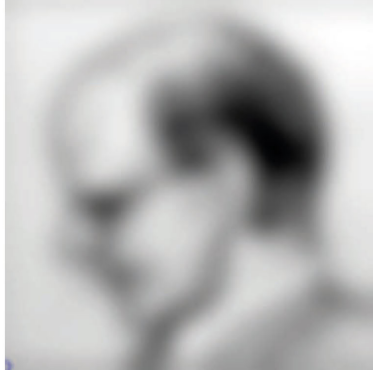
FT



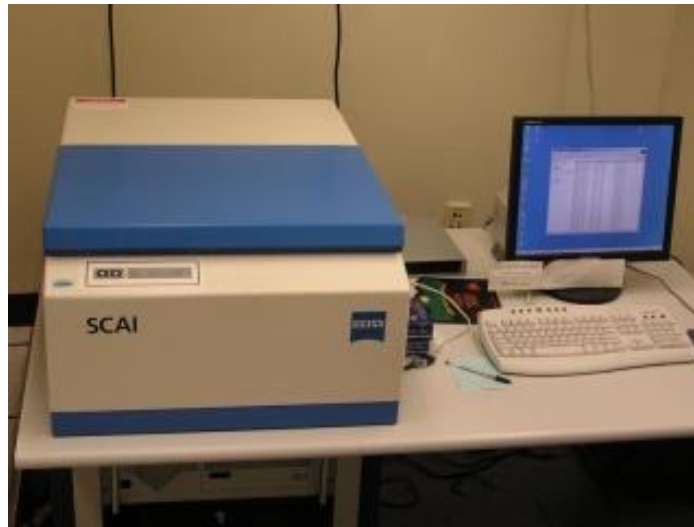
x

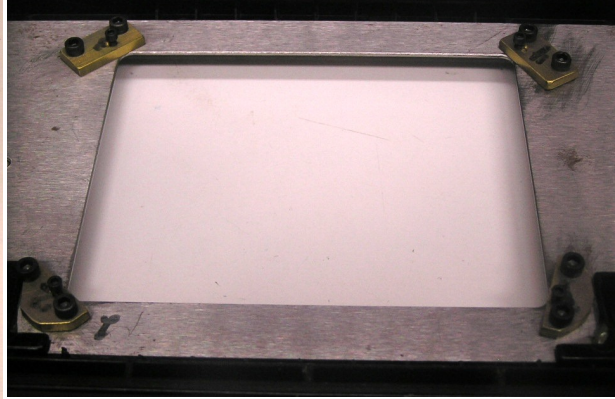


Low-pass filter

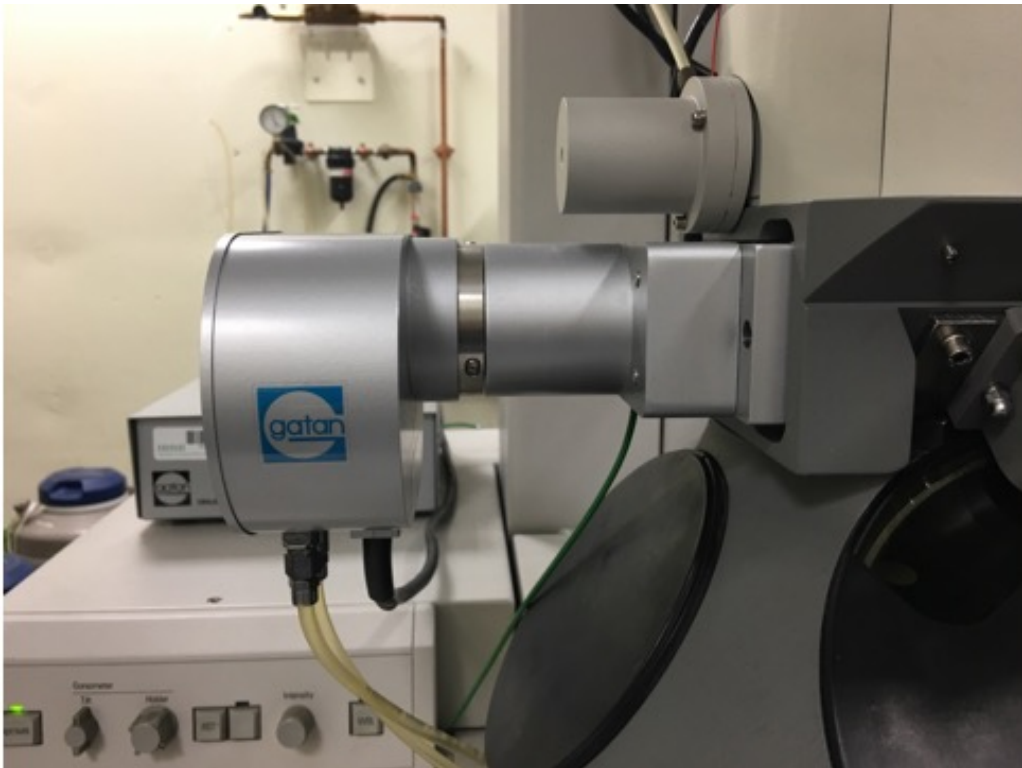


II. Cameras – from CCD to DED





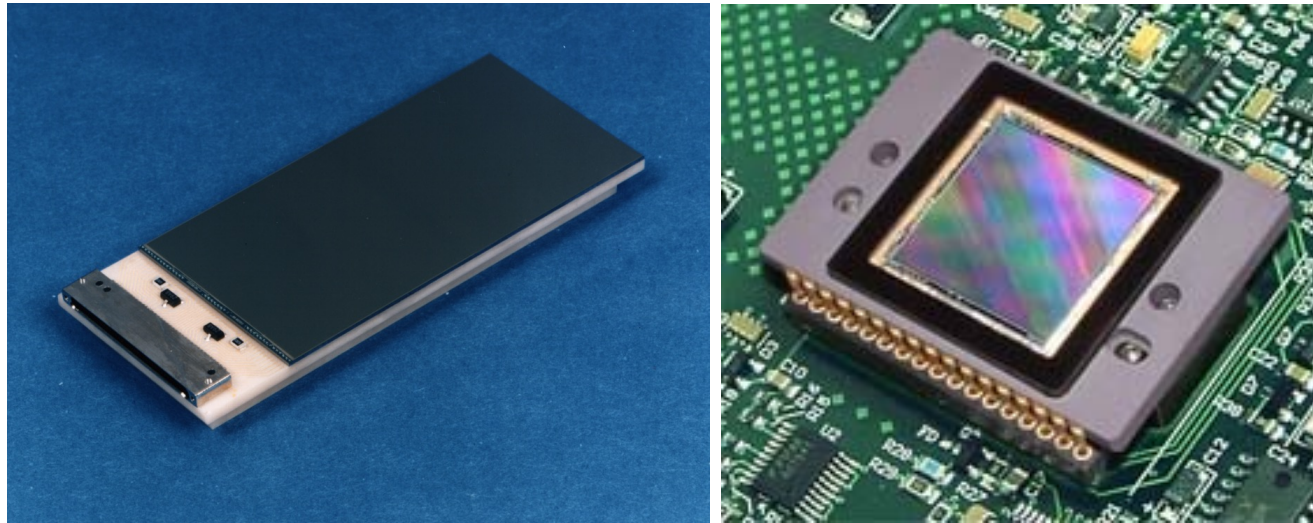
Gatan Orius CCD & TVIPS TemCam 224HD CCD cameras on CM120



What is a CCD ?

Charge Coupled Devices (CCDs) were invented in the 1970s and originally found application as memory devices. Their light sensitive properties were quickly exploited for imaging applications and they produced a major revolution in Astronomy. They improved the light gathering power of telescopes by almost two orders of magnitude. Nowadays an amateur astronomer with a CCD camera and a 15 cm telescope can collect as much light as an astronomer of the 1960s equipped with a photographic plate and a 1m telescope.

CCDs work by converting light into a pattern of electronic charge in a silicon chip. This pattern of charge is converted into a video waveform, digitized and stored as an image file on a computer.



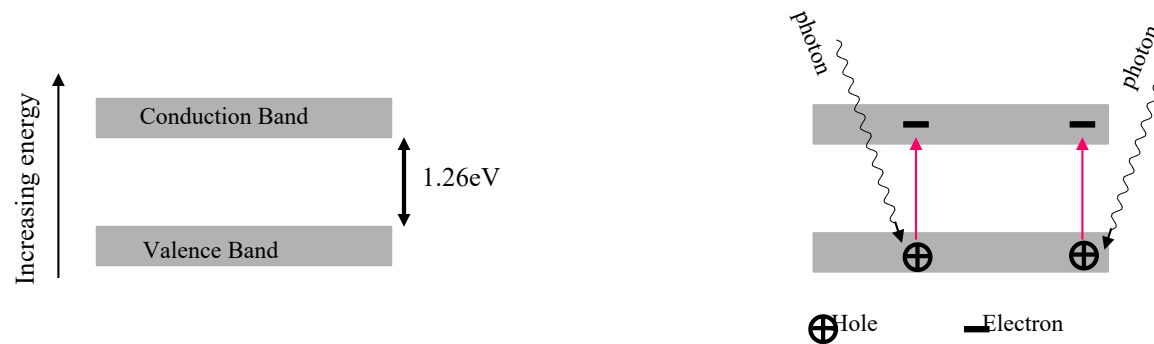
Willard S. Boyle and George E. Smith
Bell Laboratories, Murray Hill, NJ, USA

2009 Nobel Prize in Physics

“for the invention of an imaging semiconductor circuit – the CCD sensor”

Photoelectric Effect

The effect is fundamental to the operation of a CCD. Atoms in a silicon crystal have electrons arranged in discrete energy bands. The lower energy band is called the Valence Band, the upper band is the Conduction Band. Most of the electrons occupy the Valence band but can be excited into the conduction band by heating or by the absorption of a photon. The energy required for this transition is 1.26 electron volts. Once in this conduction band the electron is free to move about in the lattice of the silicon crystal. It leaves behind a 'hole' in the valence band which acts like a positively charged carrier. In the absence of an external electric field the hole and electron will quickly re-combine and be lost. In a CCD an electric field is introduced to sweep these charge carriers apart and prevent recombination.



Thermally generated electrons are indistinguishable from photo-generated electrons. They constitute a noise source known as 'Dark Current' and it is important that CCDs are kept cold to reduce their number.

1.26eV corresponds to the energy of light with a wavelength of $1\mu\text{m}$. Beyond this wavelength silicon becomes transparent and CCDs constructed from silicon become insensitive.

CCD signal readout

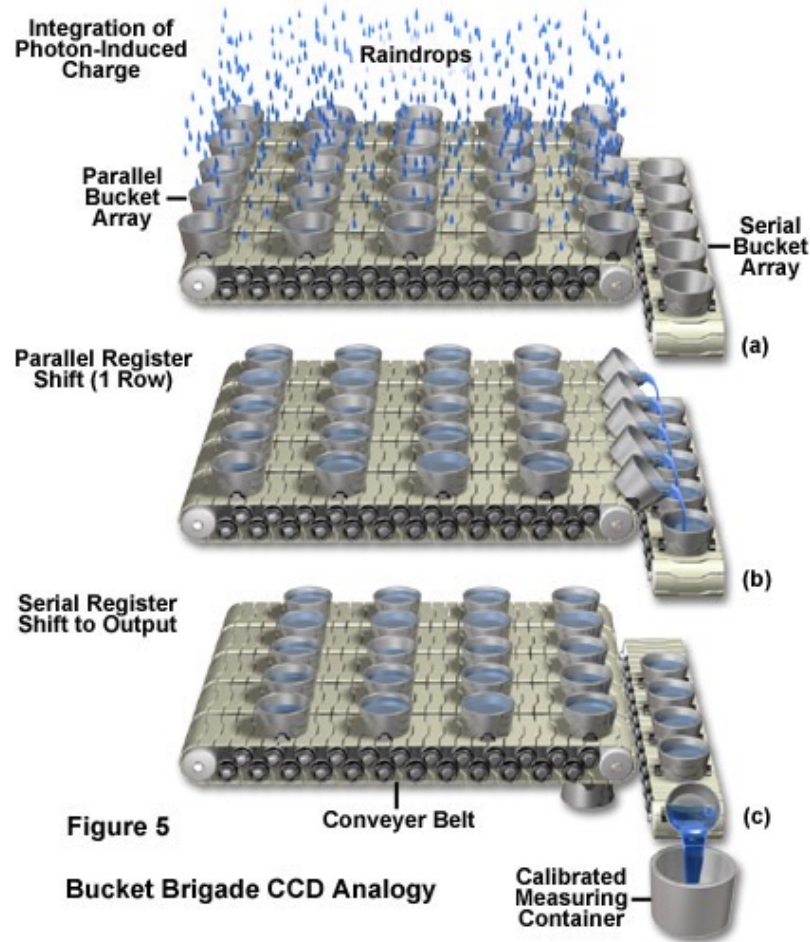
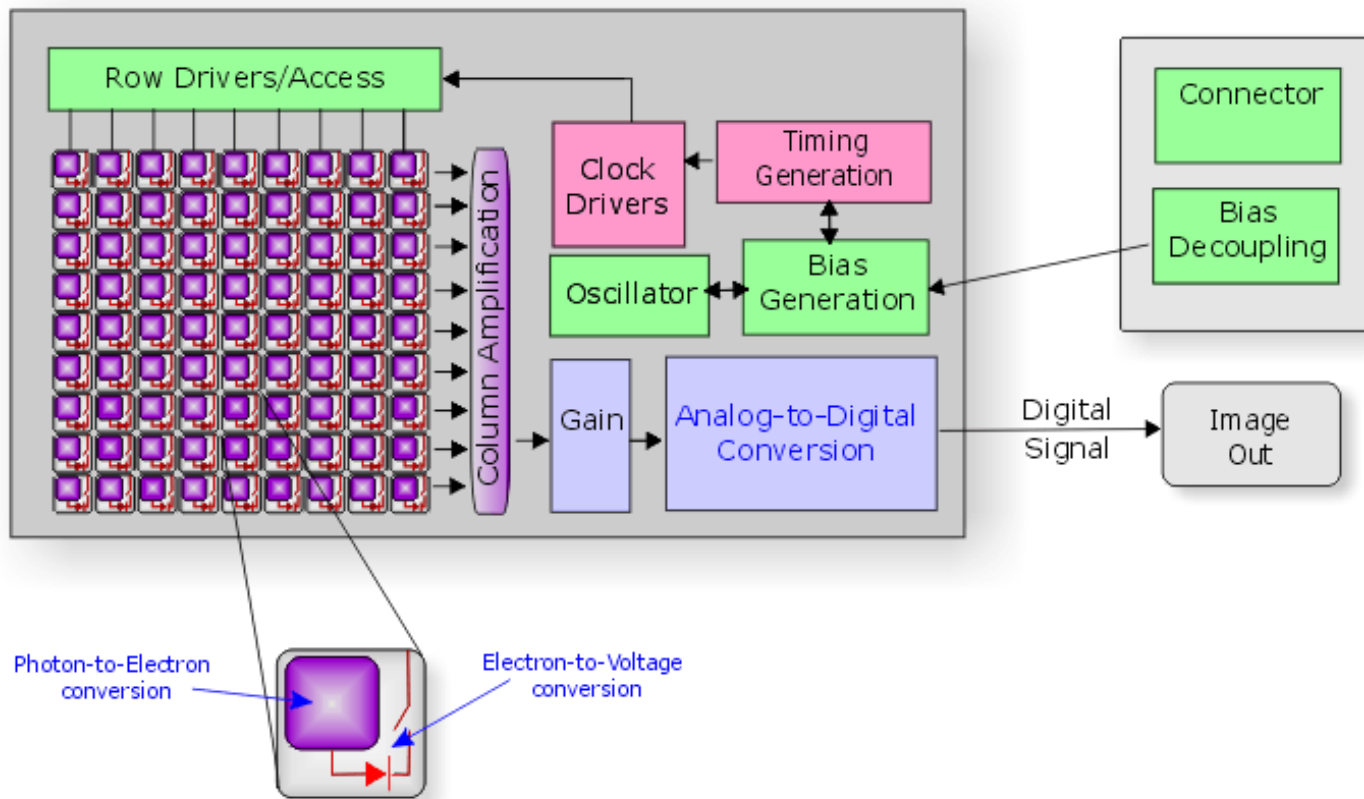


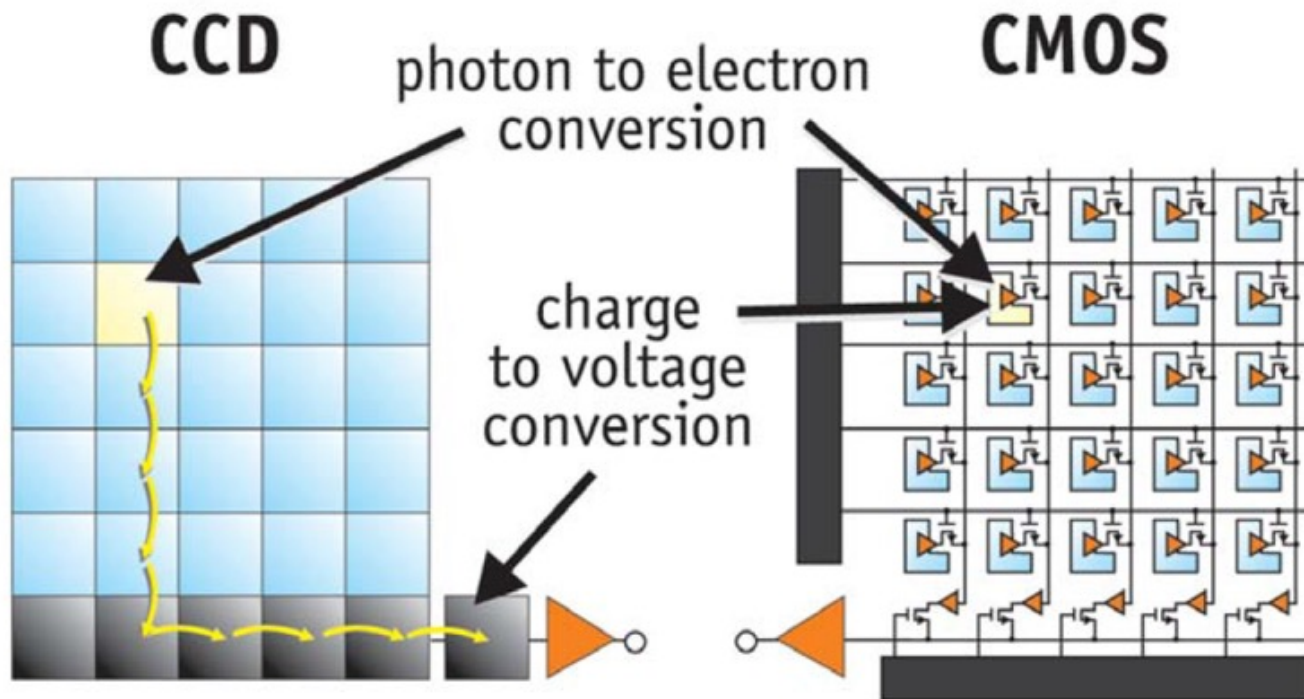
Figure 5
Bucket Brigade CCD Analogy

CMOS

Complementary Metal Oxide Semiconductor Device

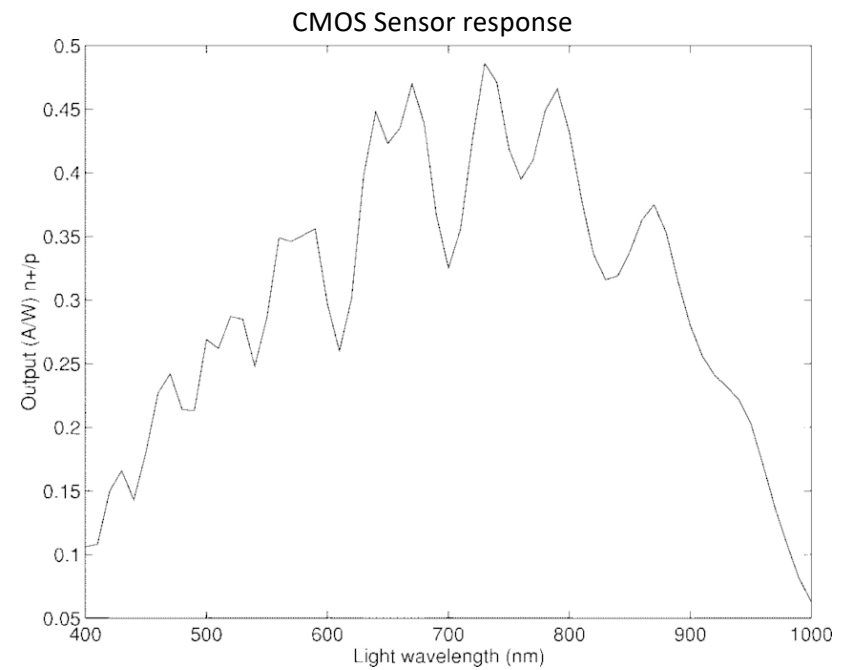
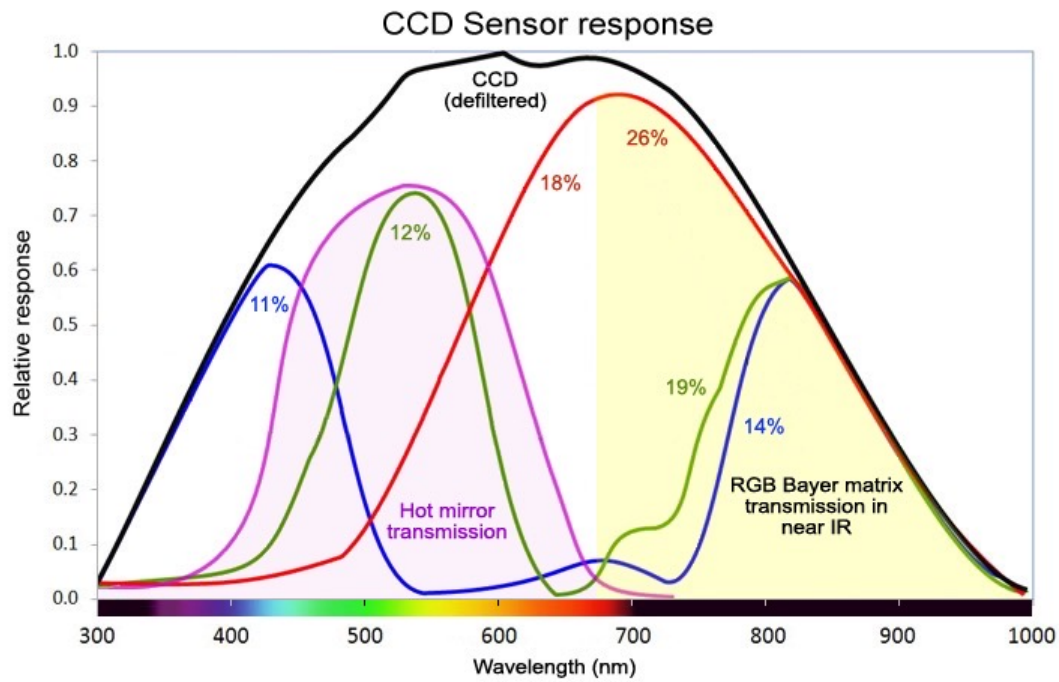
Camera Circuit Board





CCDs move photogenerated charge from pixel to pixel and convert it to voltage at an output node. CMOS imagers convert charge to voltage inside each pixel.

Spectral Responses for CCD and CMOS Sensors



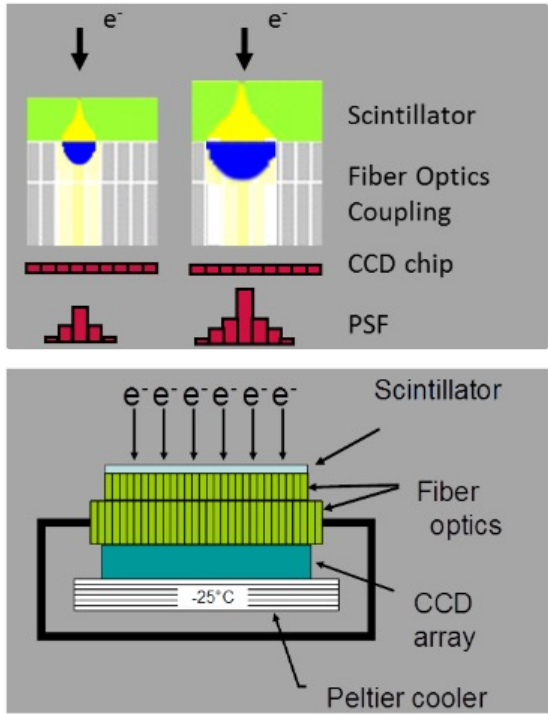
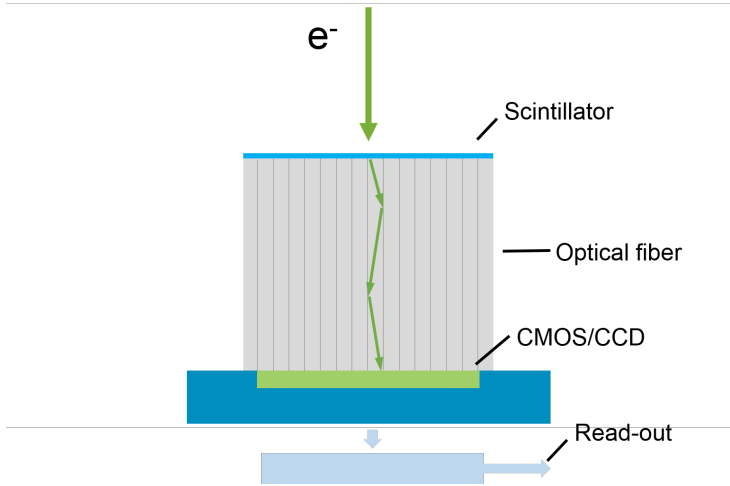
For TEM, the electrons need to be converted to photon signal so that the developed technology of CCD can be used.

Two Key Questions for a Camera

- 1. How is the voltage signal generated, from electron or photon?**
- 2. How is the voltage signal read out?**

Electron to Photon Conversion in Scintillator layer Results in Information Loss

CCD: multi stage conversion of electron energy via fiber or lens optics



For cryoEM sample, with conventional camera with scintillator, it is difficult to get resolution better than 1 nm!

Direct Electron Detector (DED)

DED with CMOS “Monolithic Active Pixel Sensors”

- Primary electron generates 100-300 electrons in P⁻ Epilayer
- Electrons collect in closest well and have to be read out frequently
- Backscatter still a big problem unless substrate is severely thinned (from 700 μm to 30-50 μm)

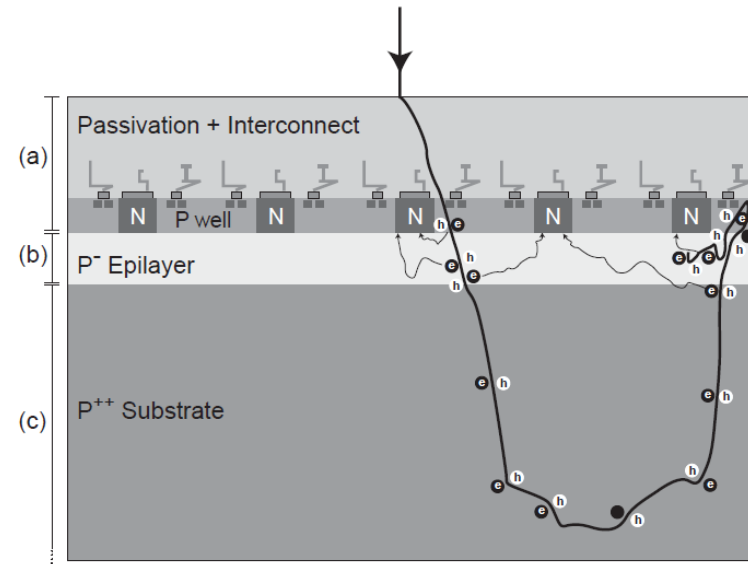
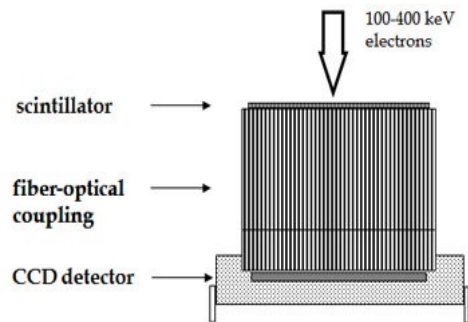


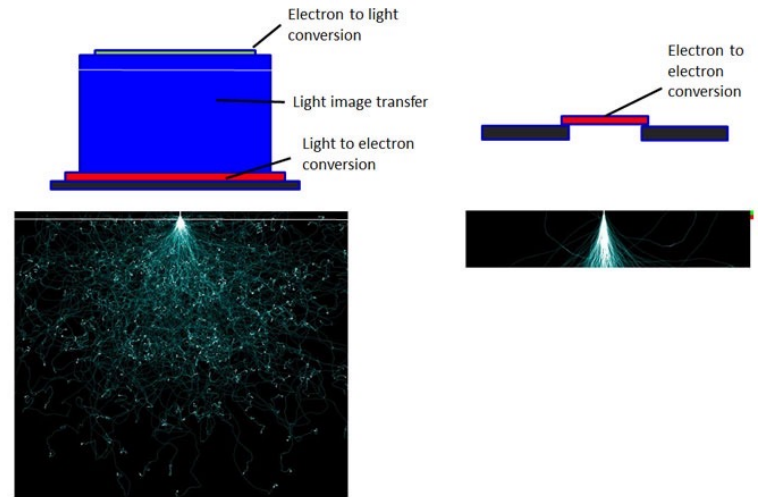
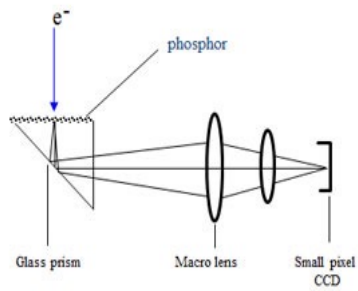
Fig. 1. Schematic of MAPS detector shown in cross-section. The detector has three main regions: (a) about 5- μm -thick passivation layer plus interconnections for readout electronics in the P well, (b) a few microns of lightly doped epilayer where the useful signal is generated, and drifts on to N wells prior to being read out, and (c) the main bulk of the detector, the substrate, which is heavily doped and which does not play a significant role in the detection process. A possible path for a single incident high-energy electron is shown to illustrate the problem with backscatter from the substrate.

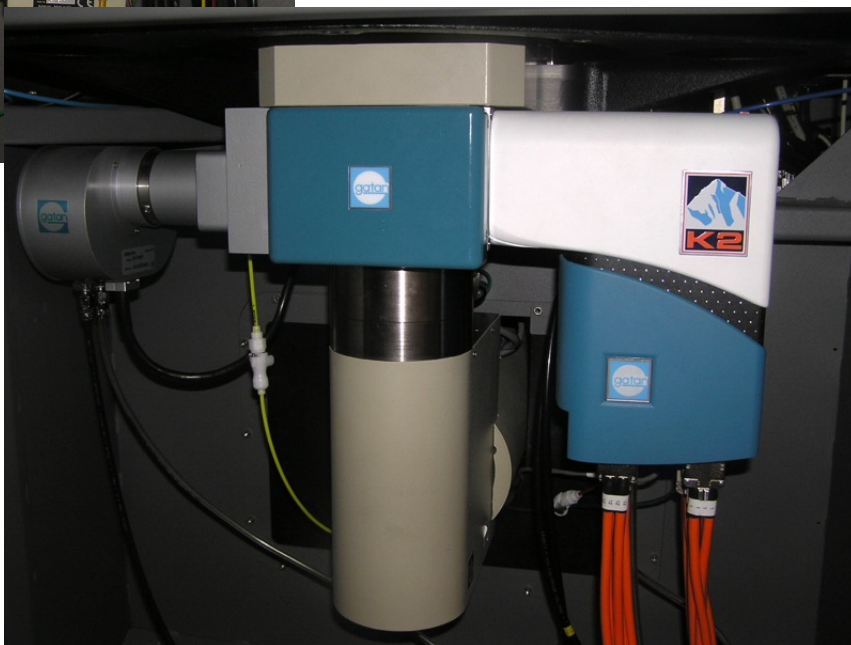
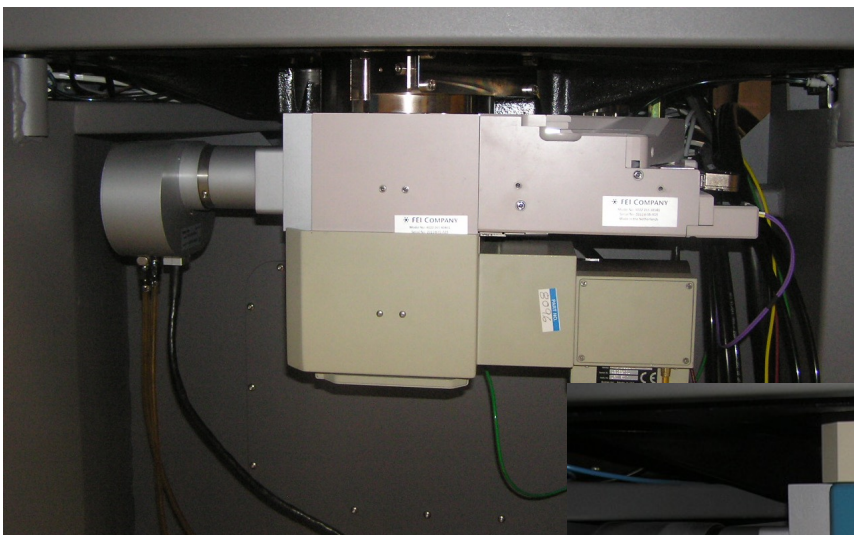
CCD vs. DED

Fiber Optical Coupling

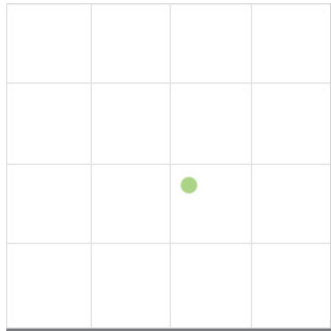


Lens Coupling

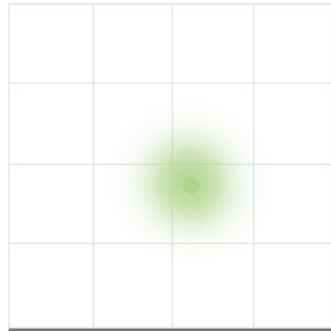




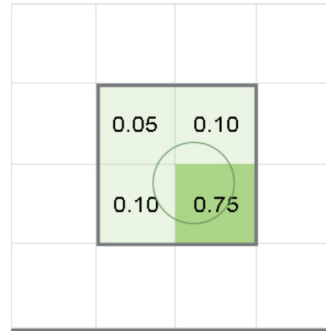
Integration vs Counting



Electron enters detector.



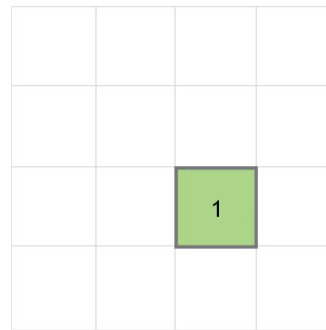
Electron signal is scattered.



Charge collects in each pixel.

Integration

- Short exposures
- High Dose-rates applications
- Lower DQE



Events reduced to highest charge pixels.

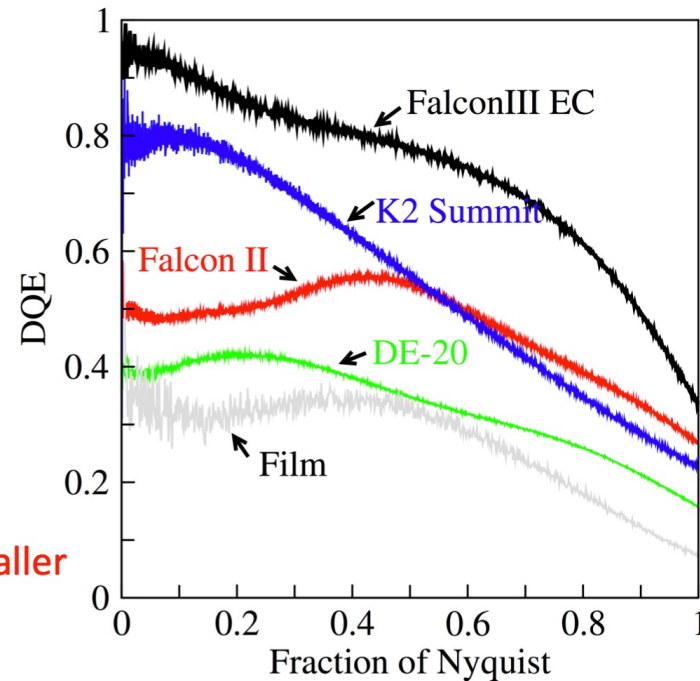
Counting

- Very low dose rate (0.5-5 e-/pixel/sec)
- Fast frame rates
- Long exposures
- Higher DQE

Detection Quantum Efficiency (DQE)

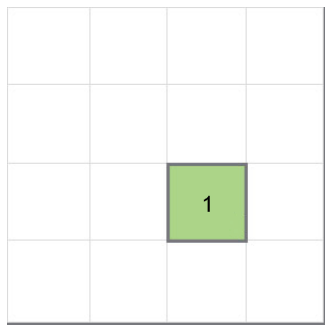
- Detective Quantum Efficiency
- $DQE = SNR_o^2 / SNR_i^2$
- A measure of the signal to noise ratio degradation
- Perfect detector has DQE of 1

Counting detector advantageous for smaller complexes > boost low frequencies

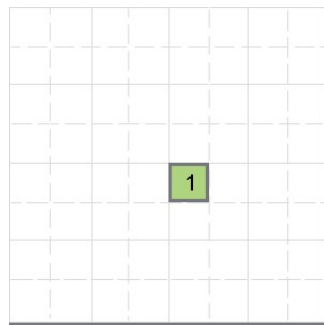


Greg McMullan

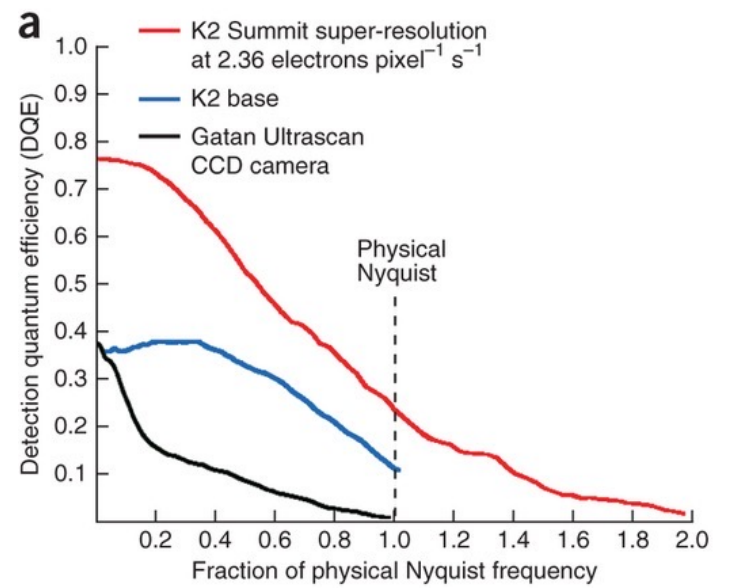
Super-resolution



Counting



Counting with Super-Res



On the Market – for high-end DED

- **Direct Electron**

 - DE-12 (4k x 3k)

 - DE-20 (5k x 4k)

 - Apollo (4k x 4k)

- **TFS**

 - Falcon 2, 3, 4 (4i)

- **Gatan**

 - K2/3 Summit

- **Others.....**

Apollo

Direct Electron[®]
PROPELLING DISCOVERY

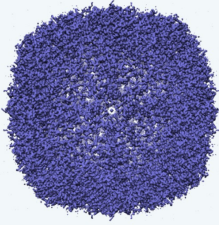
World's First Event-Based Active Pixel Direct Detector

- Our novel direct detection device (DDD[®]) delivers **ultra-low noise** and **extraordinary resolution** for almost **any beam brightness**.
- **Electron counting in hardware** through a combination of sensor technology & FPGA edge computing.
- Speed equivalent to a large-pixel direct detector **counting at 2,400 fps**.
- **On-chip CDS** minimizes noise and maximizes detection efficiency.
- **4k × 4k** (16.8 million) physical pixels with larger **8 μm pixel size** to maximize resolution (MTF).
- **Super-resolution** 8k × 8k (67.1 MP) readout to the computer at **60 fps** for motion correction, dose filtering, etc.
- Elegant, powerful, and **easy-to-use** for cryo-EM.
- Integrated with SerialEM for **automated** data acquisition.



EMD-33707

Single-particle
1.47 Å



[3D View](#)
[Gallery](#)

Deposition: 27/06/2022
 Map released: 20/07/2022
 Last modified: 20/07/2022

- Overview
- 3D View
- Sample
- Experiment
- Validation
- Volume Browser
- Additional data
- Links

EMD-33707

[Download](#)

Apoferritin structure at 1.46 angstrom resolution by CryoARM300 equipped with Apollo

Sample Organism: [Mus musculus](#)

Sample: [Apoferritin](#)

Raw data: [EMPIAR-11101](#)

Deposition Authors: [Bammes B](#), [Spilman M](#), [Sakamoto M](#), [Fukumura T](#), [Konyuba Y](#), [Okunishi E](#)

[Apoferritin structure at 1.46 angstrom resolution by CryoARM300 equipped with Apollo](#)

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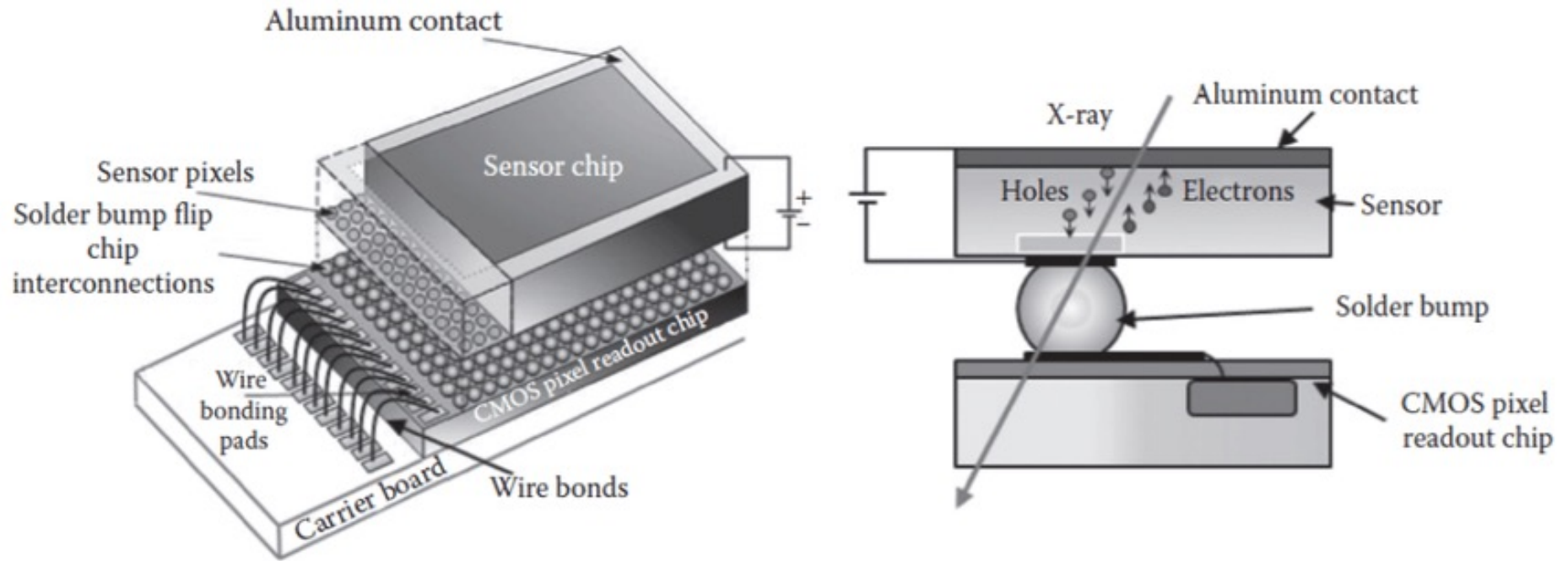
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Hybrid-Pixel Camera – a different type of DED



- **Ionizing radiation type of detector (semiconductor sensor + ASIC readout chip)**
- **Solder bump to couple them together (hybrid)**

Hybrid-Pixel Camera – a different type of DED

- Direct (electron) detector with good DQE
- Noiseless
- **Very high readout frame rate (4500Hz, 8bit)**
- 30-200 keV
- ~ 512 x 512 – 1000 x 1000 pixels
- Pixel size **75** um
- Commonly used in X-ray and synchrotron beam line
- Very good for diffraction data



Singla, Quadro, ELA



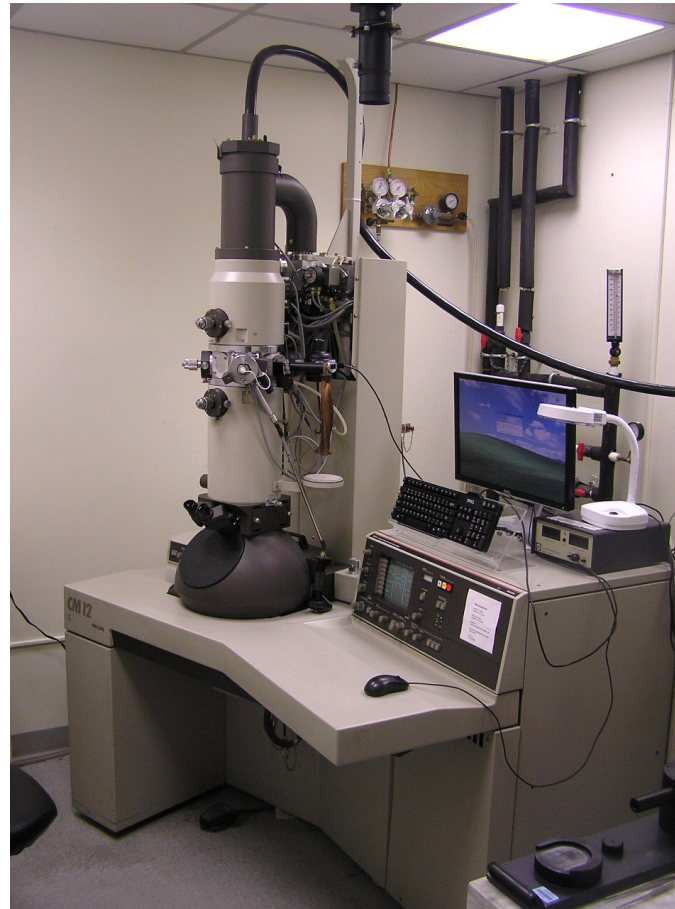
CheeTa - Diffraction

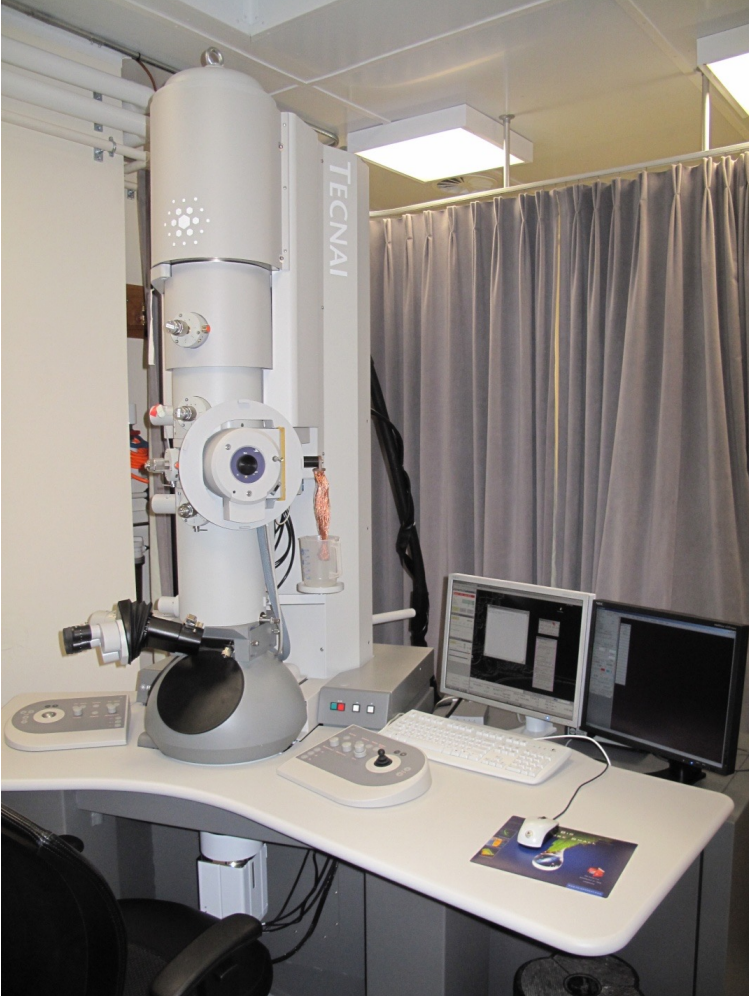


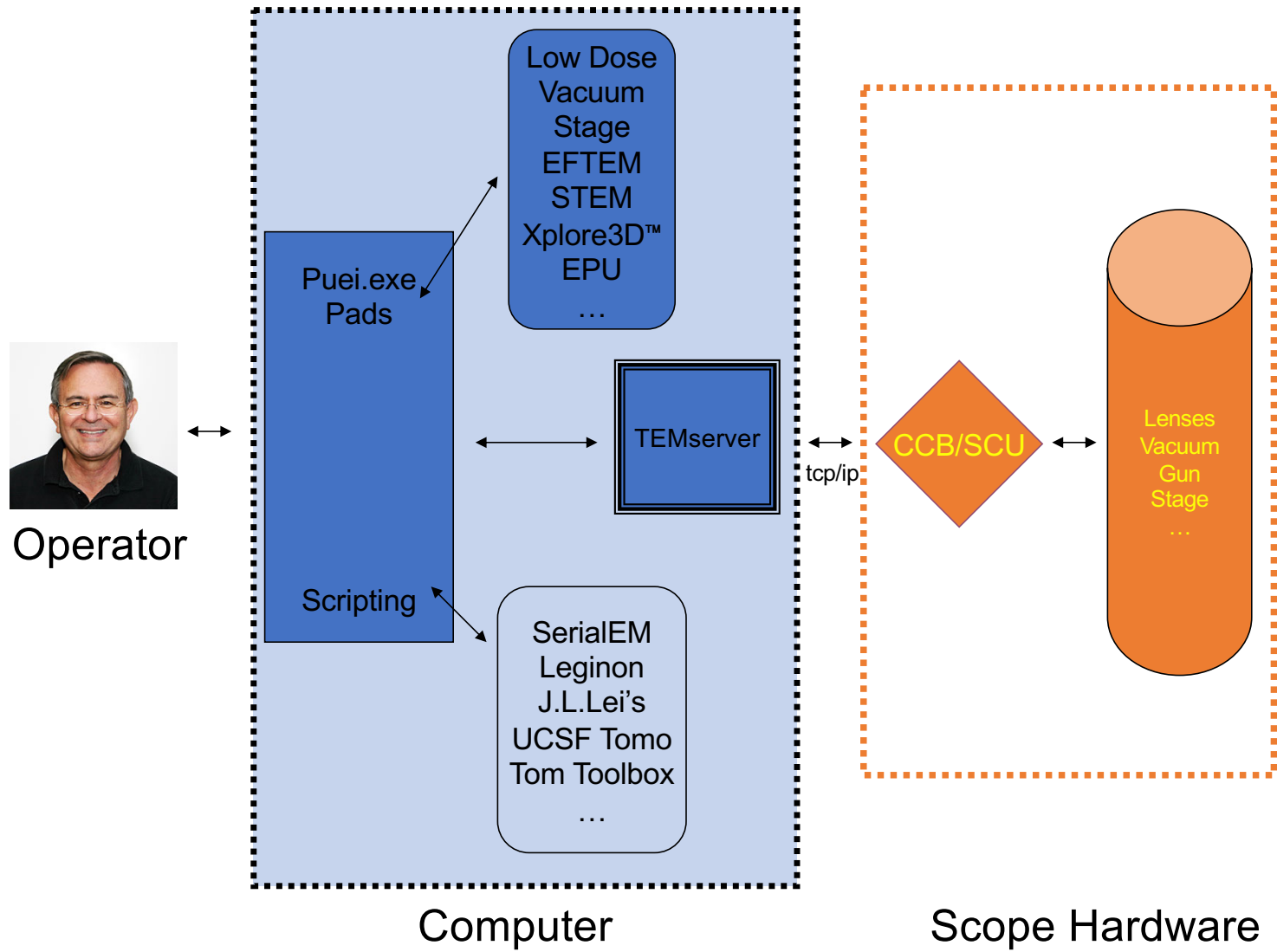
Stela – 4D STEM

III. Advanced Software Control

From Analog to Digital

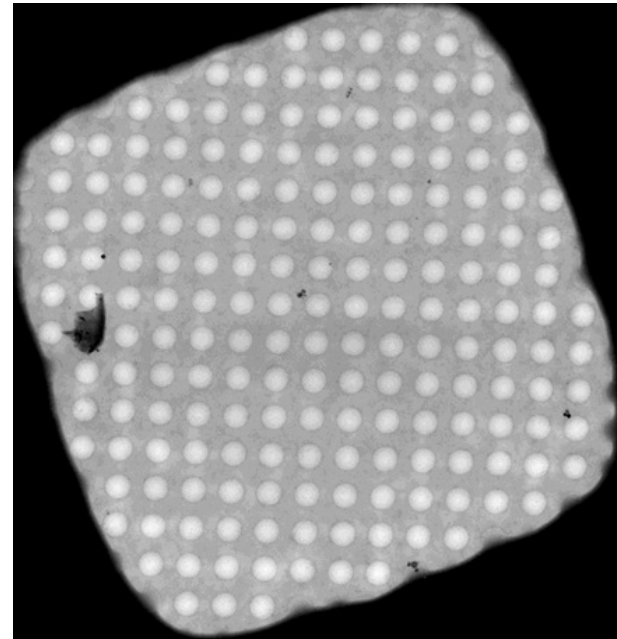






The Task of a TEM Operator

- With the best beam conditions, then
- Go to a spot - $x, y, z, \alpha, (\beta)$
- Focus
- Record
- (repeat)



THANK YOU